



Smart DE Glove as assistancetools for digital production environments

Conceptual presentation and preliminary studies on the development of a smart materials based haptic and sensory glove

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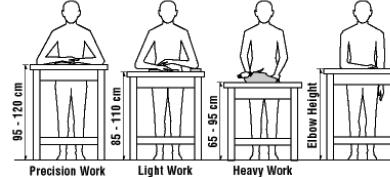
Quality control



Safety control



Ergonomics



Intelligent haptic assistance tool

Documentation



Haptic Feedback



Education



Communication



user input





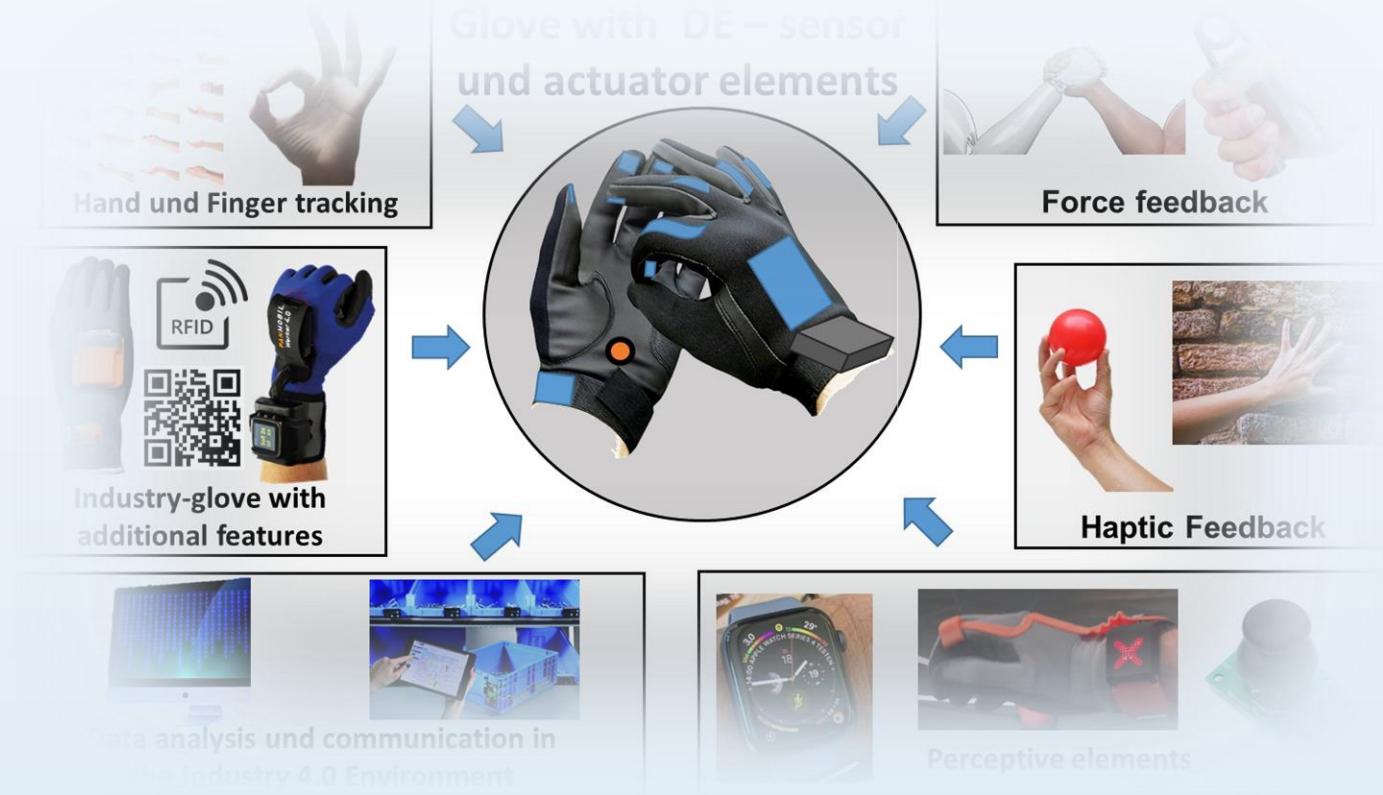
Structure of the assistance tool

- sensor
- actuator
- electronic
- integration

Prototype assembly

Prototype validation

Summary and outlook





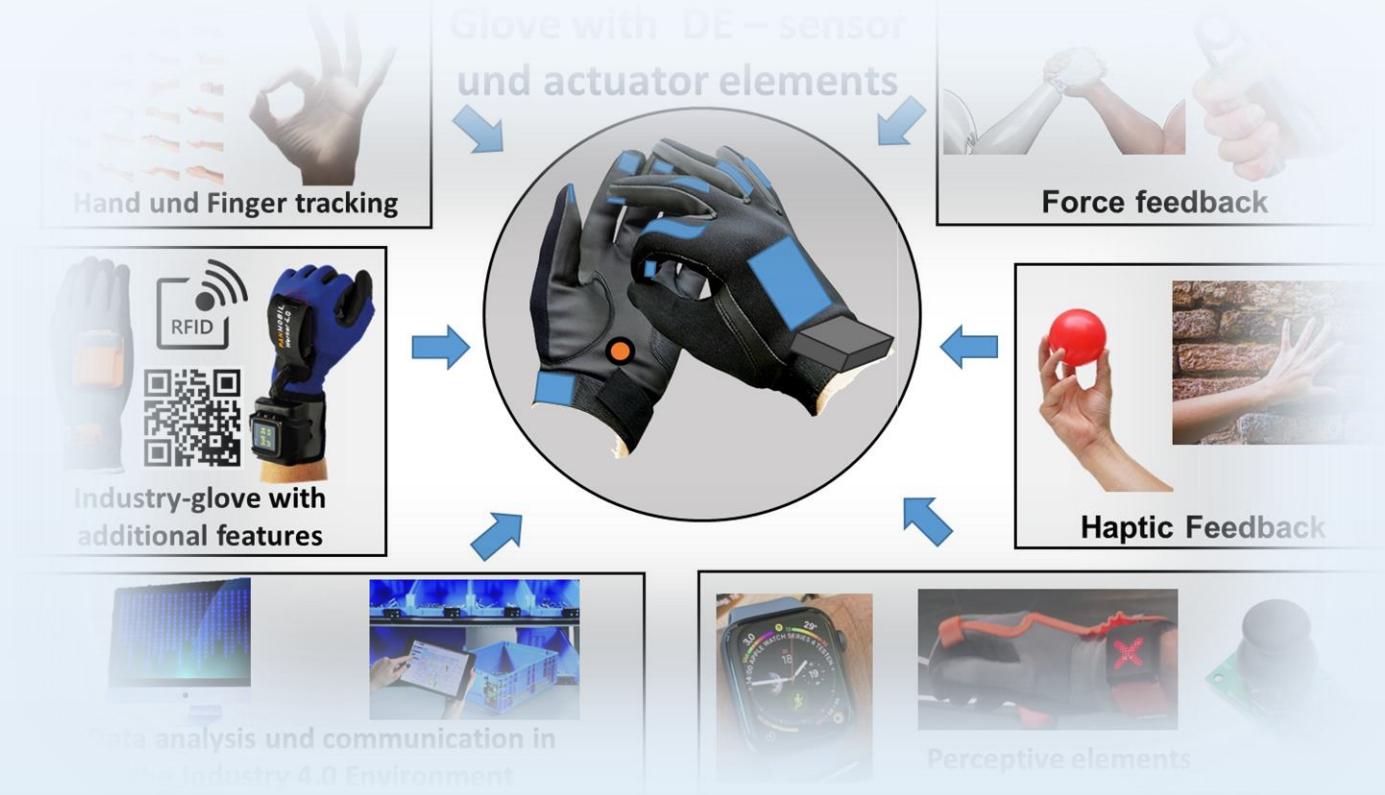
Structure of the assistance tool

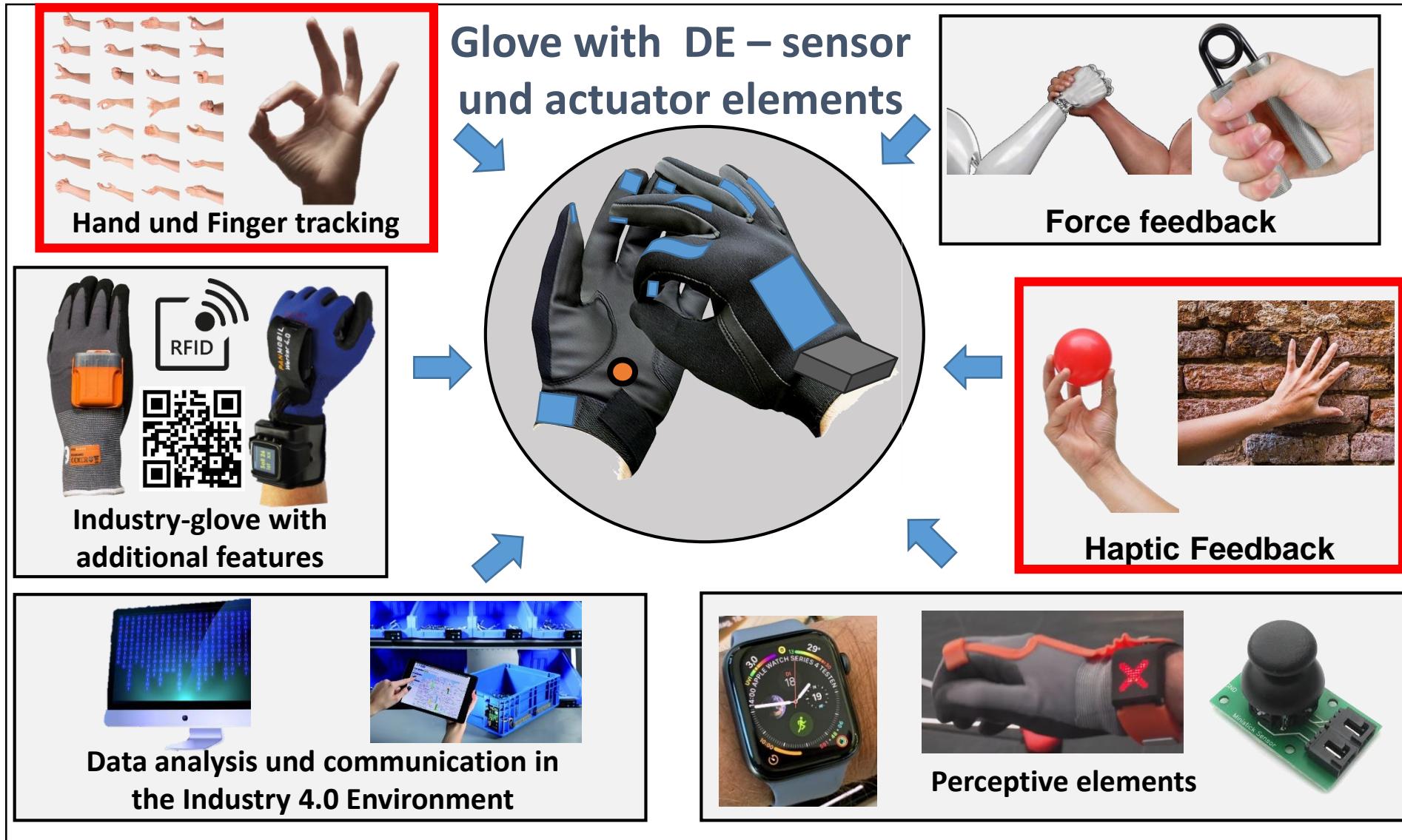
- sensor
- actuator
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Prototype assembly

Prototype validation

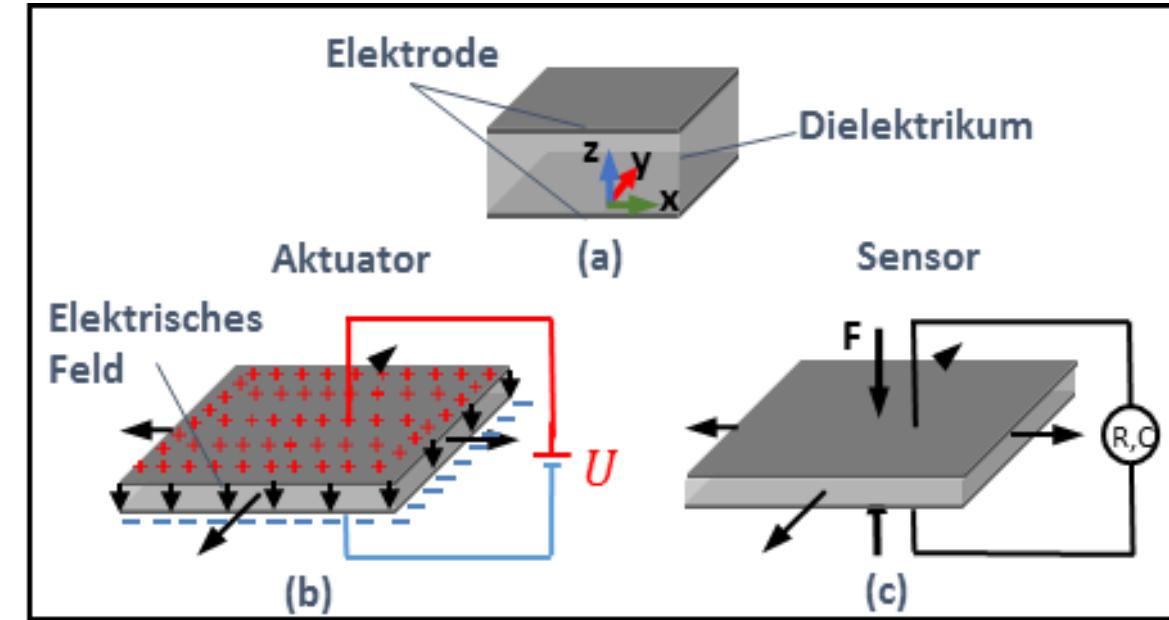
Summary and outlook



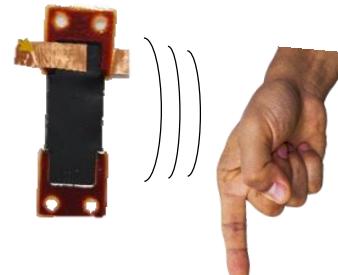




actuator



Vibration



Force pulse



Displacement



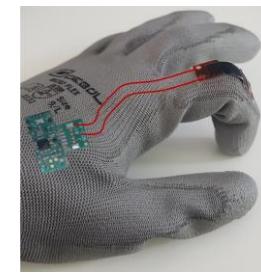
Increased rigidity

sensor

Force



Pressure

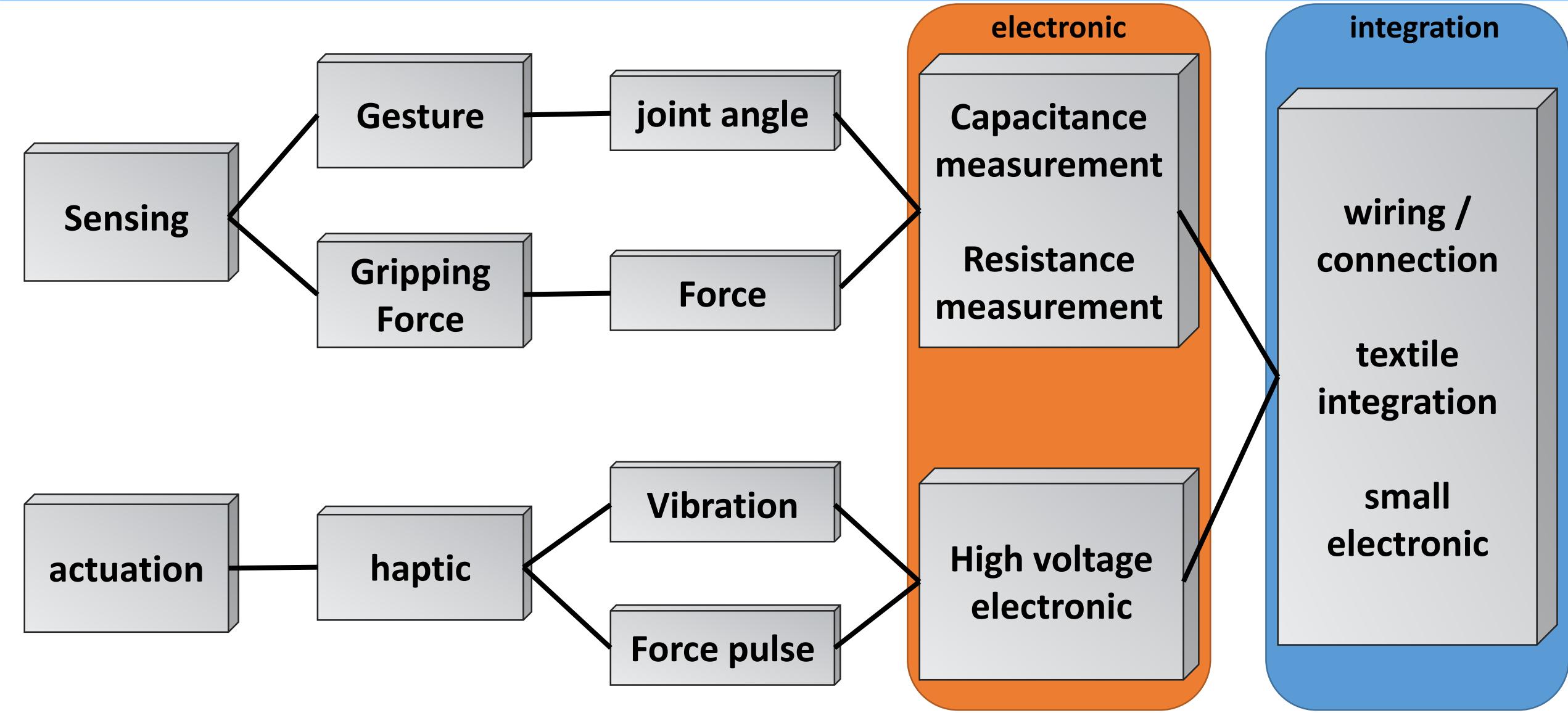


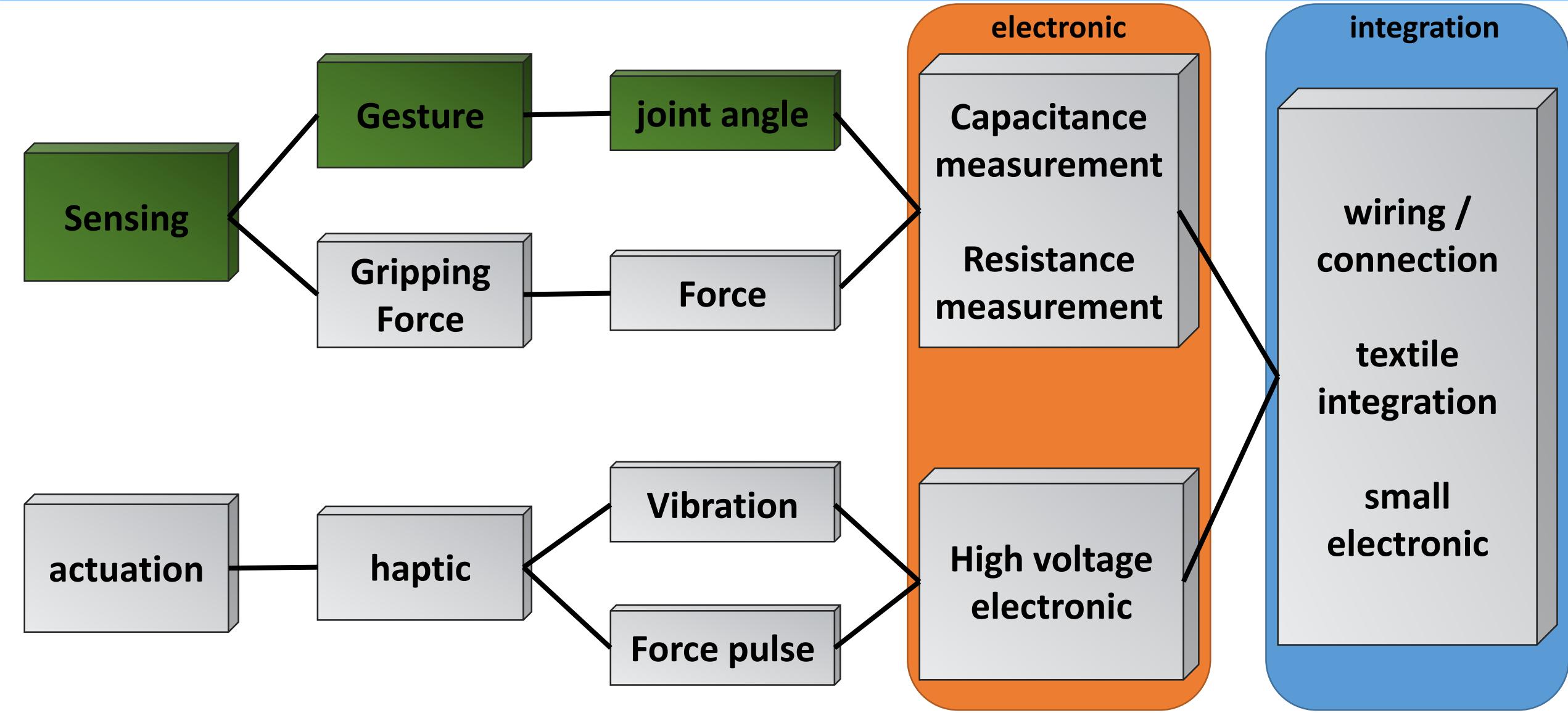
stretch



angle

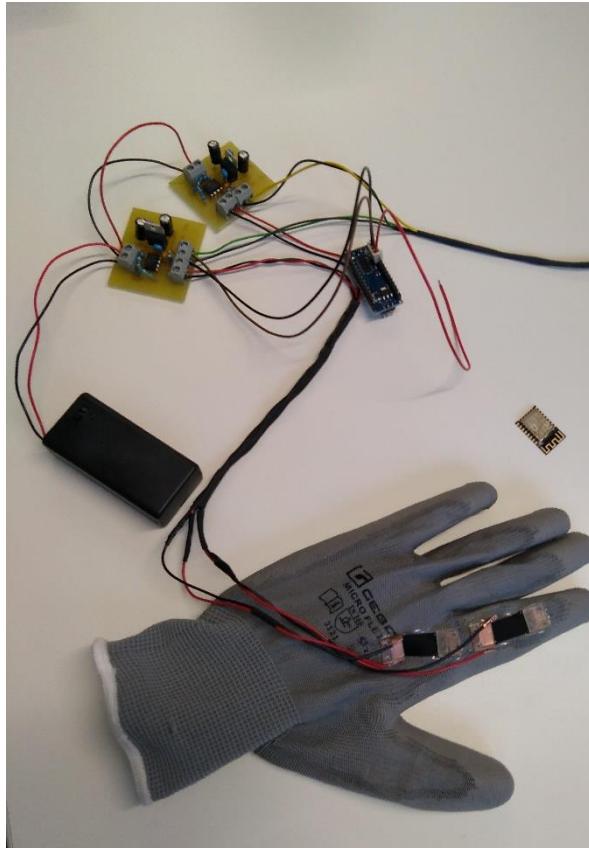
<http://solutions.parker.com/FlexSenseKit>

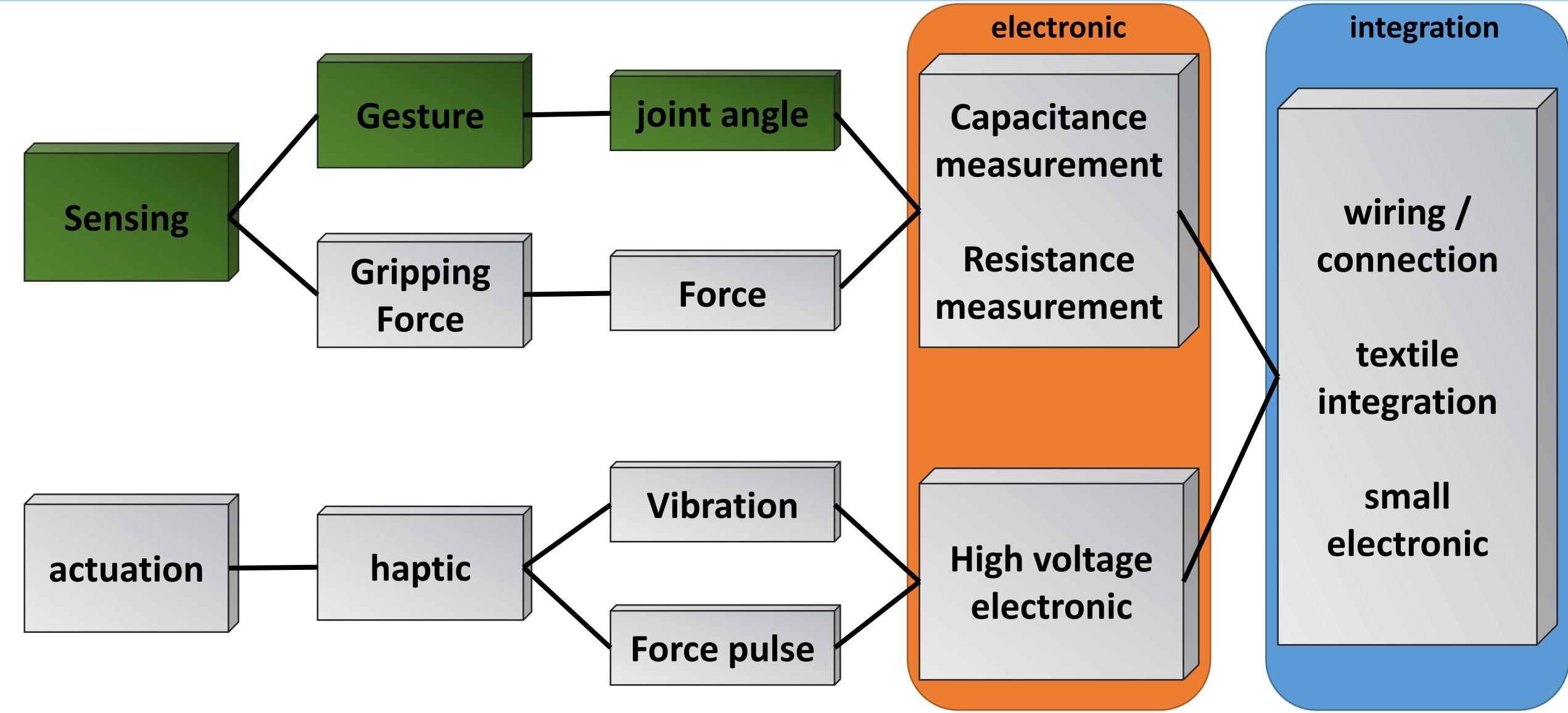


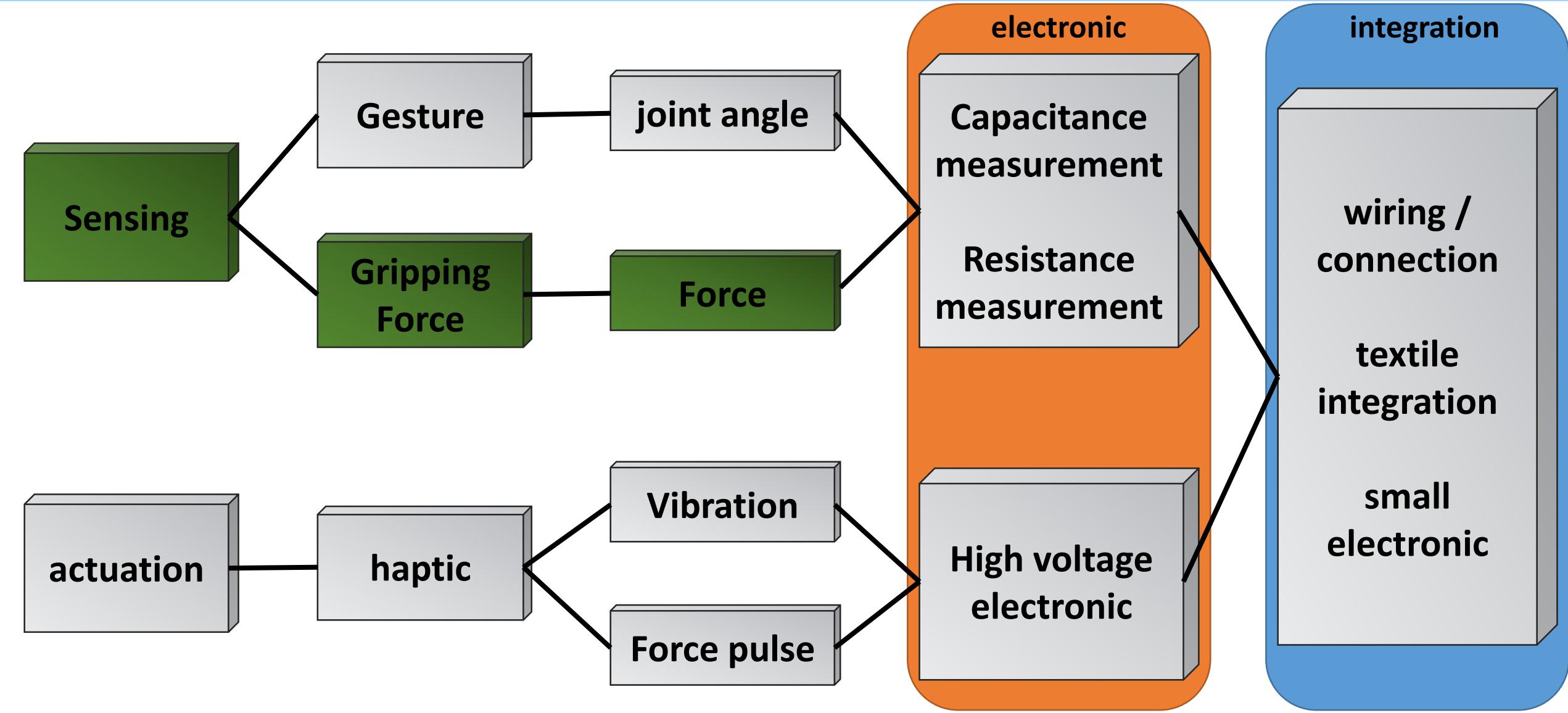




First Prototype test









pressing forces



tightening forces



Activation / safty



Tightening torque



Directional forces



communication



low force



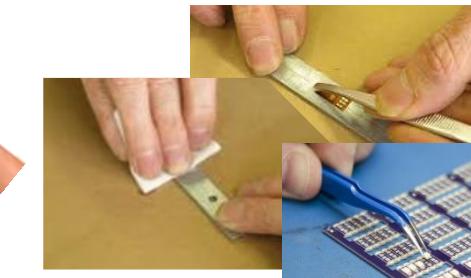
weight force



mounting force



Tool force

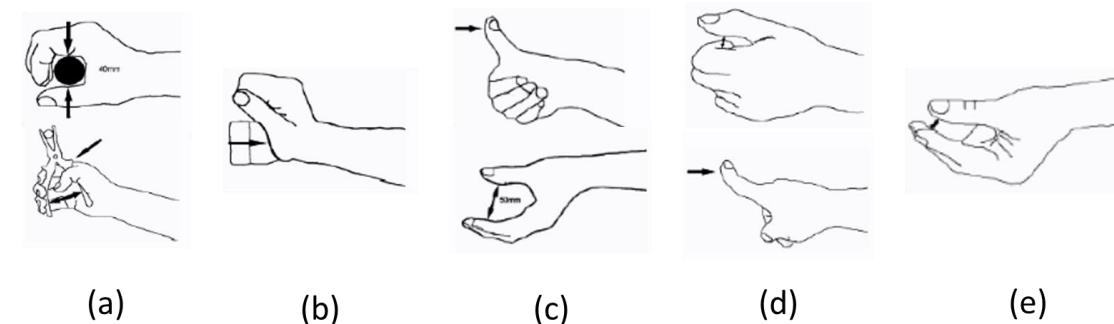


fine force



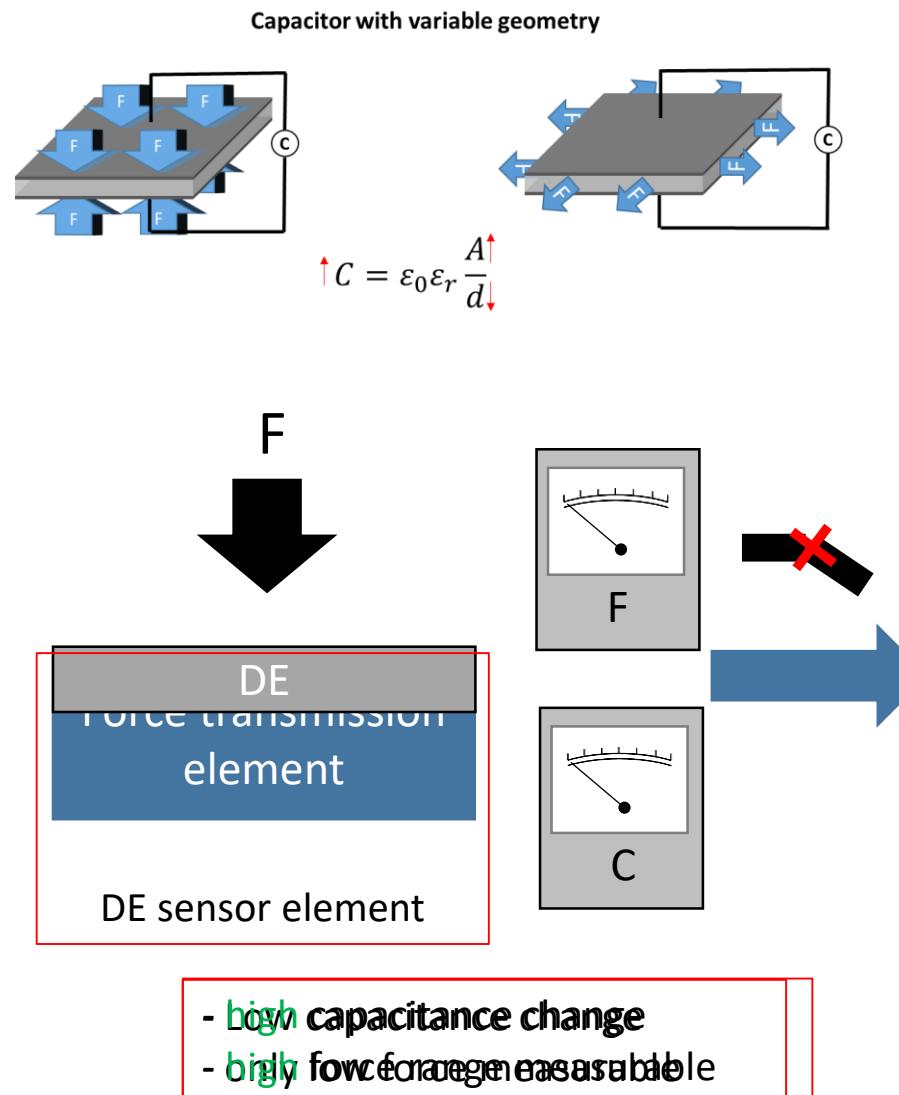
Component shape

Mainly used hand positions and corresponding maximum allowed forces

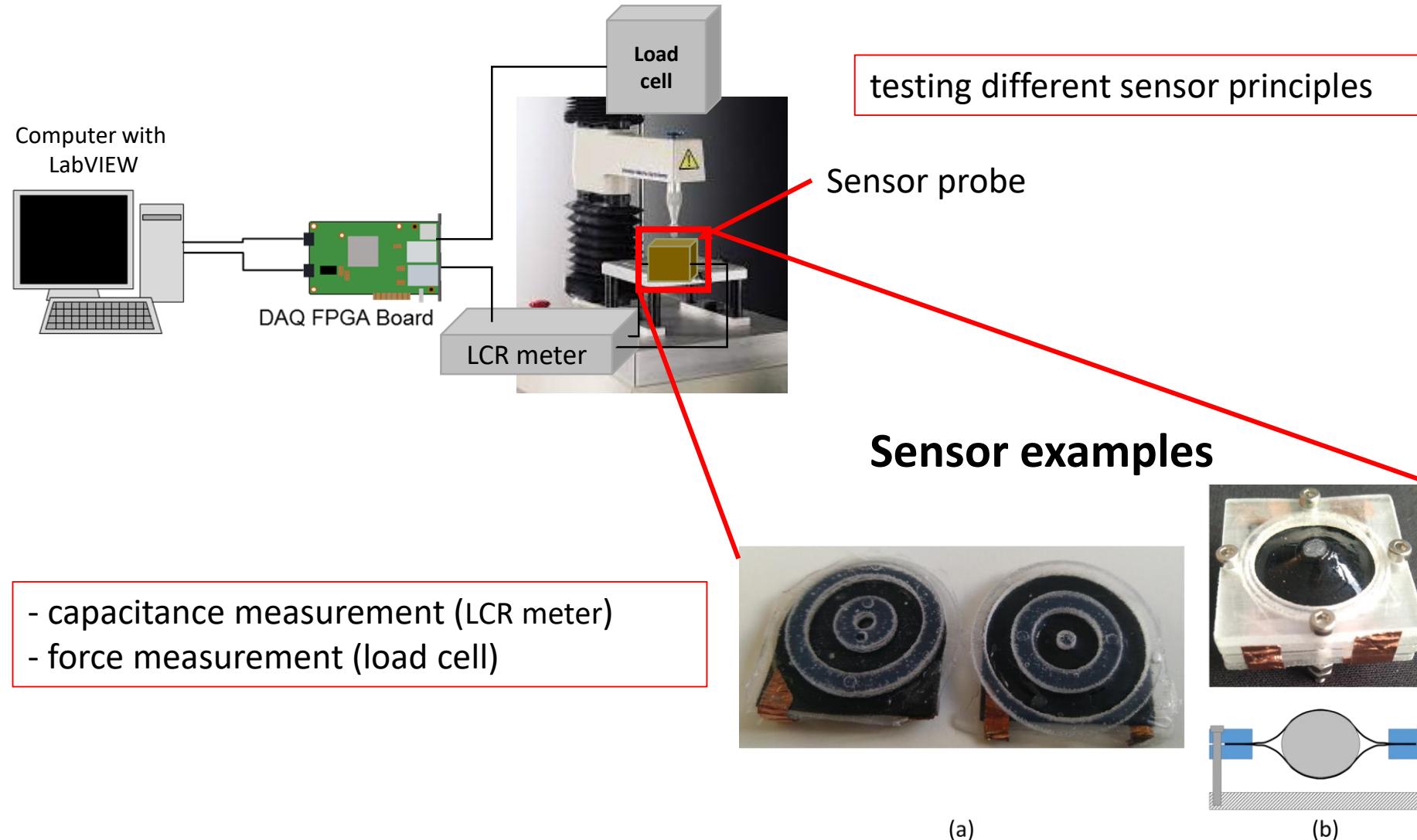


Grasp	Force (N)							
	fine			continue / often	"normal"			maximal
	0,50%	1%	2%		10%	33%	50%	
(a) Span	0,9	1,8	3,6	18	60	90	120	180
(b) Palm push	0,825	1,65	3,3	16,5	55	82,5	110	165
(c) Thumb push	0,35	0,7	1,4	7	23,3	35	46,7	70
(d) Finger push/pinch	0,25	0,5	1	5	16,7	25	33,3	50
(e) Finger slide	0,05	0,1	0,2	1	3,3	5	6,7	10

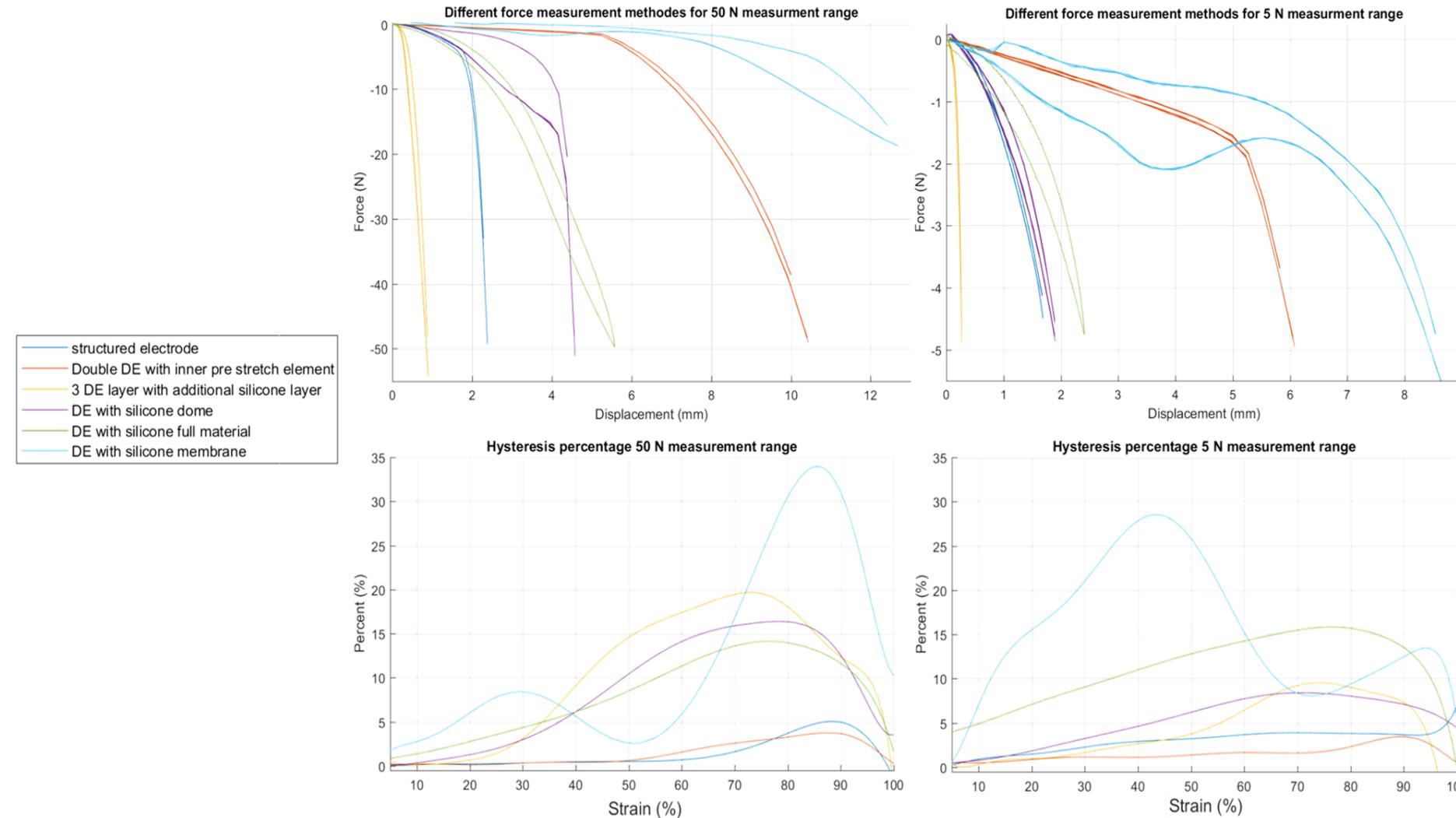
For the different movements of the hand the forces to be measured vary from millinewton range to several hundred Newton



Nr.	Geometry / measurement principle	Description
(a)		Single DE layer
(b)		Single DE layer clamped
(c)		Multiple DE layers with additional silicone layer
(d)		DE + flexible pre stretch element
(e)		DE + metal spring
(f)		DE + metal element
(g)		DE with structured Electrode
(h)		DE + silicone membrane
(i)		Double DE + inner pre stretch element



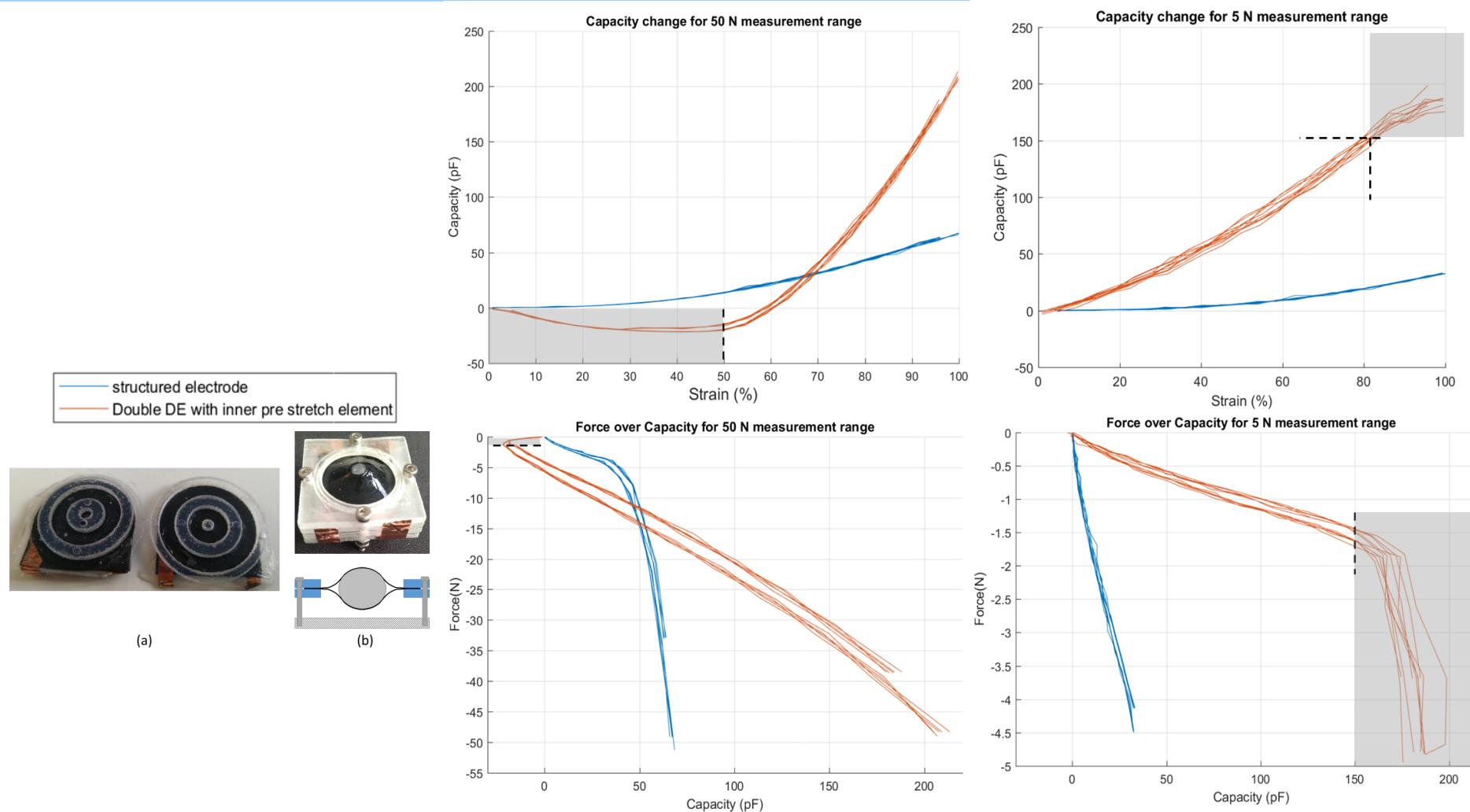
Comparison of different sensor principles



The different principles show hysteresis with different strength



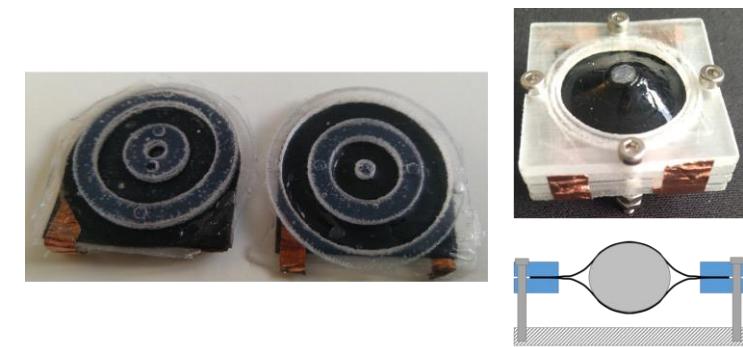
Capacity for the favorite sensor principle



force and capacitance measurement
→ force resolution and the needed capacitance resolution of the sensor element



Measurement routine:
5 measurements for every force range
with 5 measurement cycles.

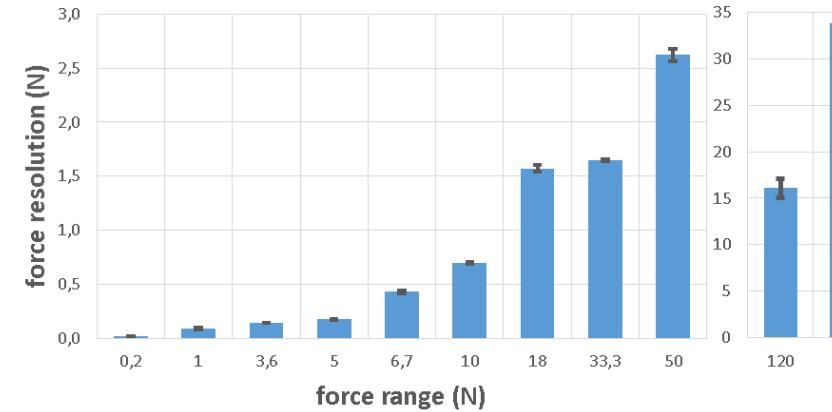


	structured DE		double DE		structured DE		double DE		structured DE		double DE		structured DE		double DE	
	3,6 N				18 N				120 N				180 N			
	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ
C min (pF)	0,185	0,106	1,256	0,138	0,415	0,063	2,779	0,291	0,769	0,427	5,826	0,169	2,536	0,861	7,006	1,092
F max (N)	0,144	0,002	0,133	0,011	1,573	0,031	1,274	0,005	16,084	0,025	6,539	0,037	33,778	0,199	12,087	0,233
	1 N				5 N				33,3 N				50 N			
	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ
C min (pF)	0,072	0,017	1,868	0,452	0,252	0,107	2,055	0,685	0,342	0,085	2,779	0,291	0,620	0,064	3,744	0,474
F max (N)	0,092	0,110	0,044	0,002	0,178	0,006	0,186	0,015	1,645	0,009	1,274	0,005	2,621	0,059	1,969	0,027
	0,2 N				1 N				6,7 N				10 N			
	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ	Q	σ
C min (pF)	0,045	0,007	1,552	0,096	0,072	0,017	1,868	0,452	0,284	0,045	0,998	0,048	0,356	0,069	2,012	0,052
F max (N)	0,022	0,003	0,022	0,003	0,092	0,110	0,044	0,002	0,434	0,012	0,239	0,003	0,701	0,009	0,416	0,005

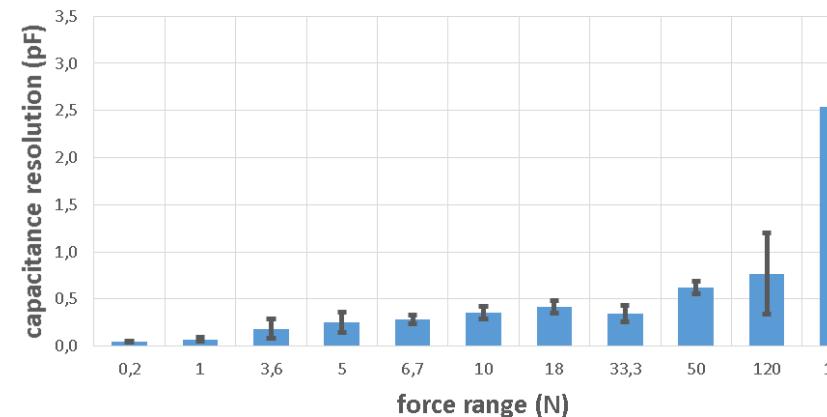
Statistic table of capacitance and force for different force range



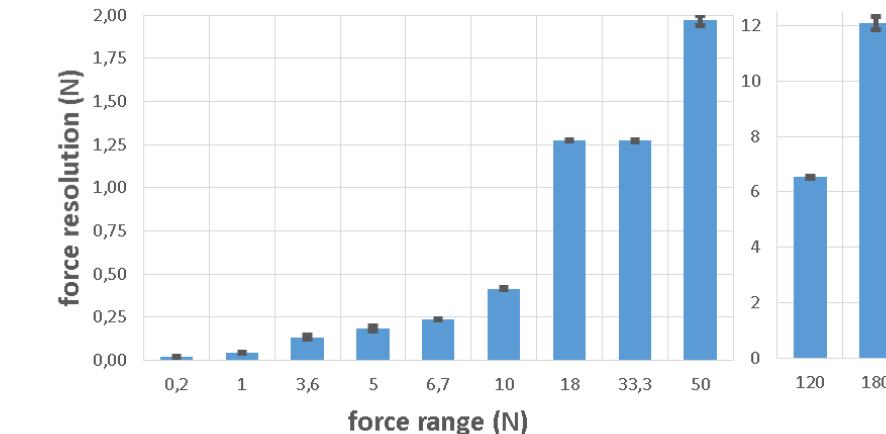
force resolution for the structured DE



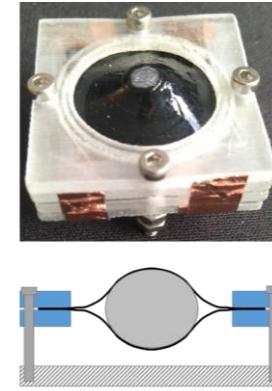
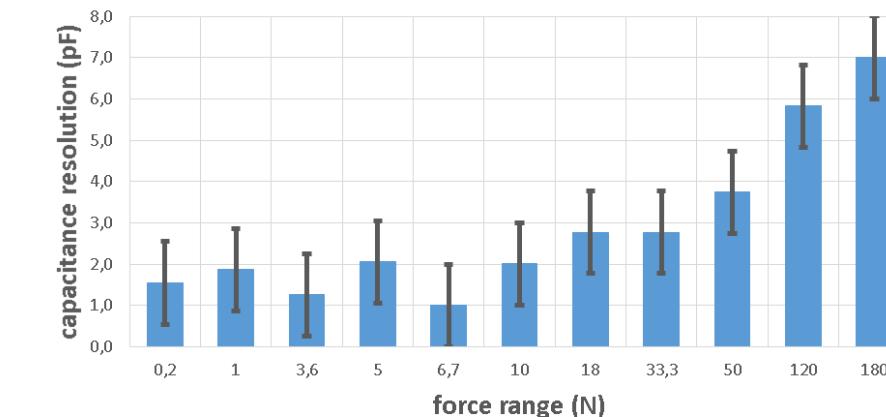
capacitance resolution for the structured DE

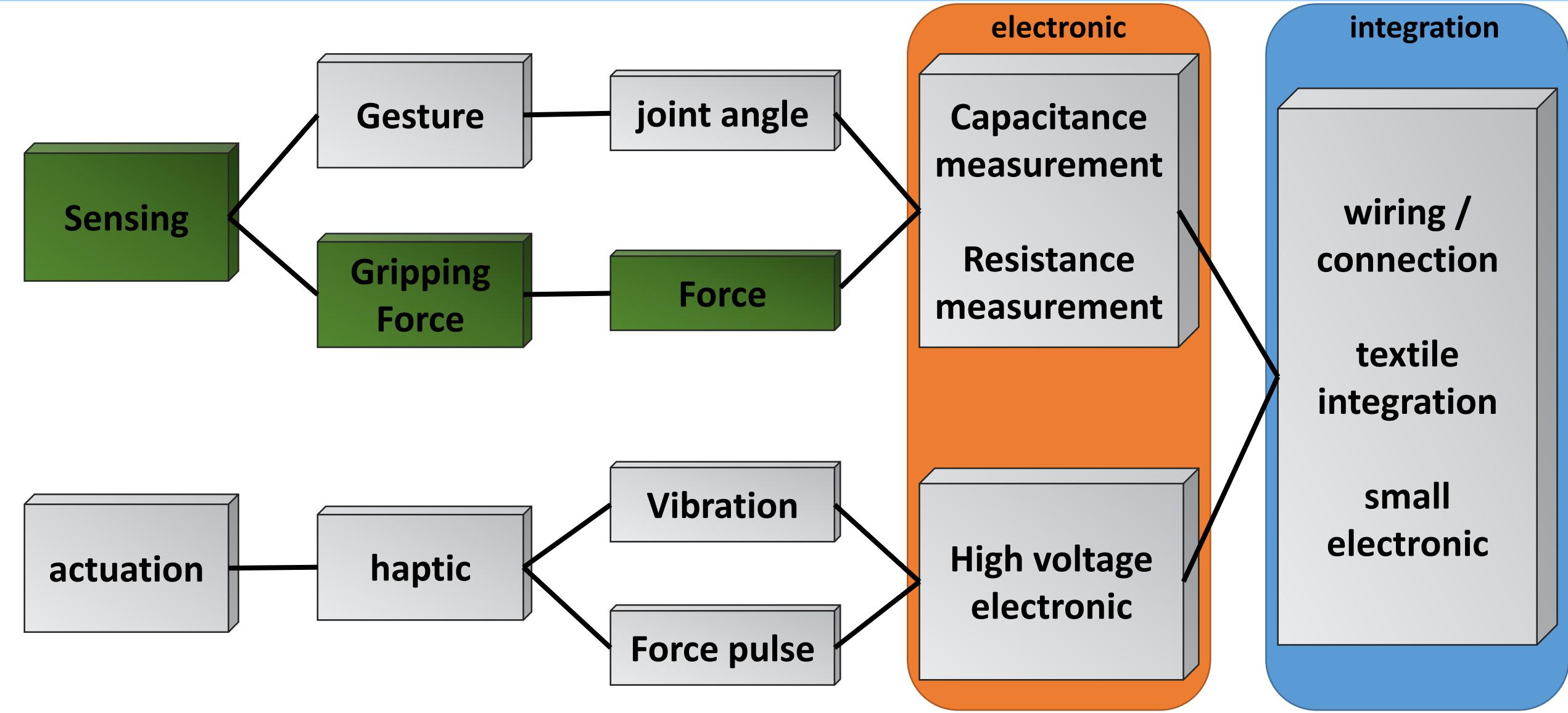


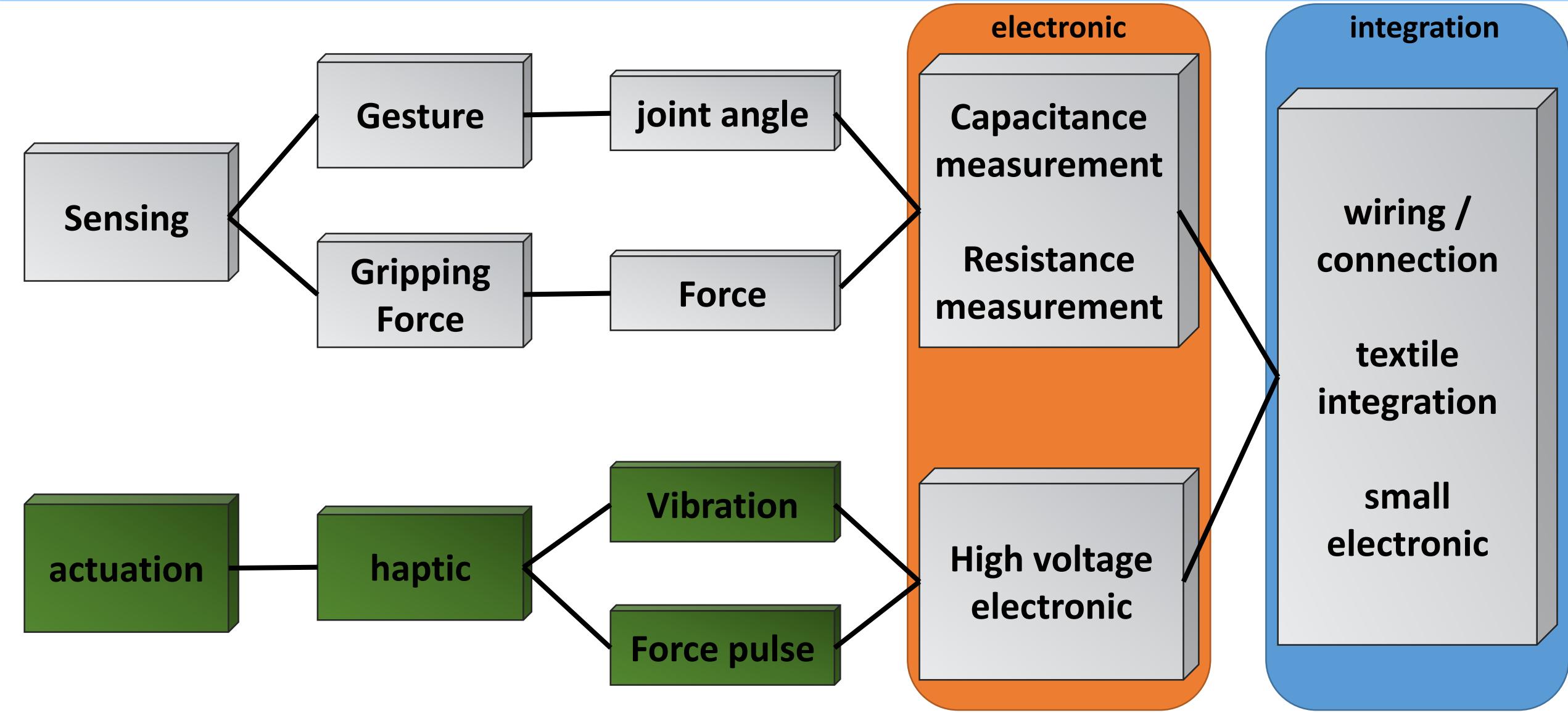
force resolution for the double DE



capacitance resolution for the double DE

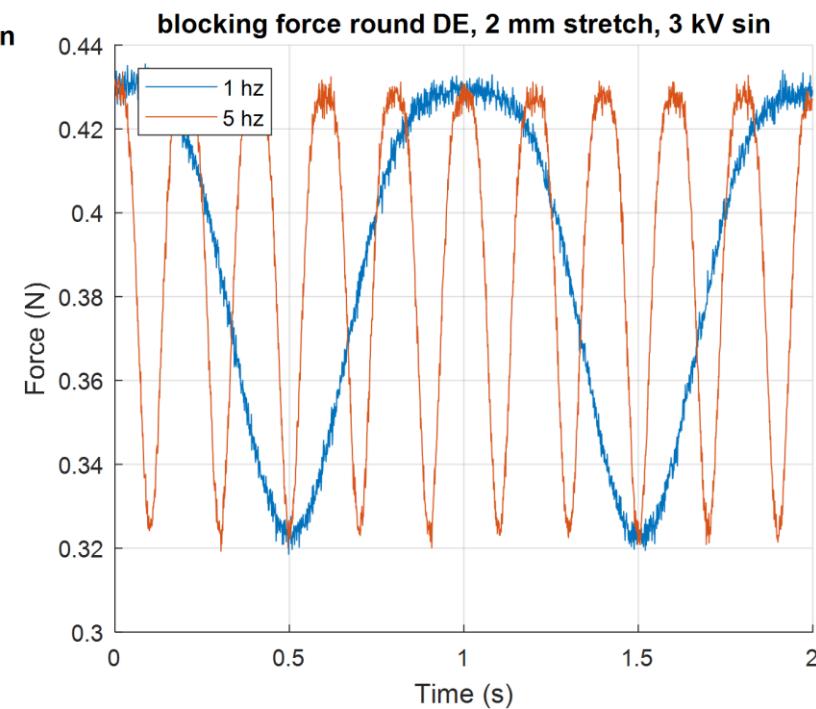
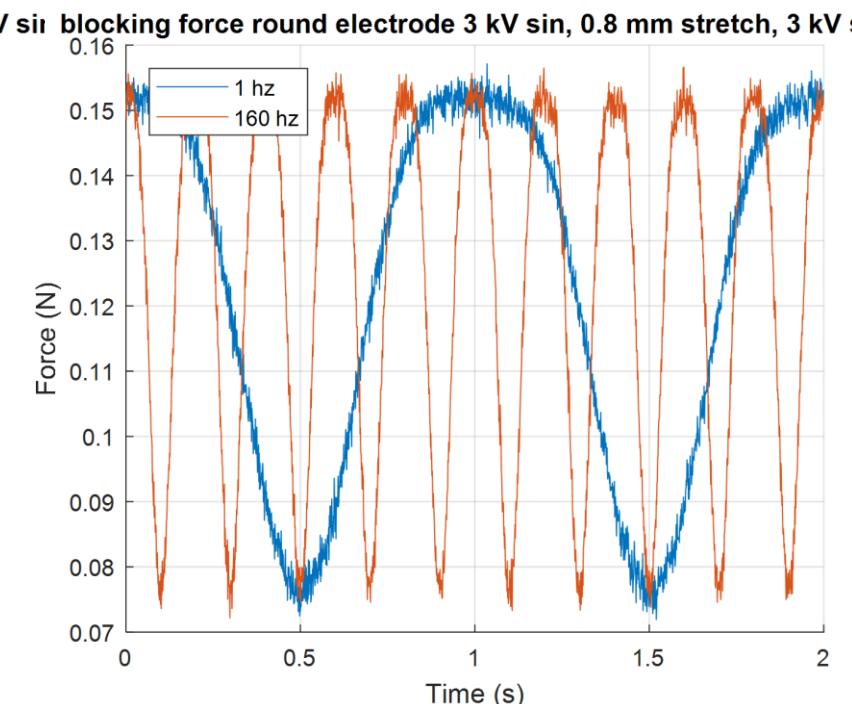
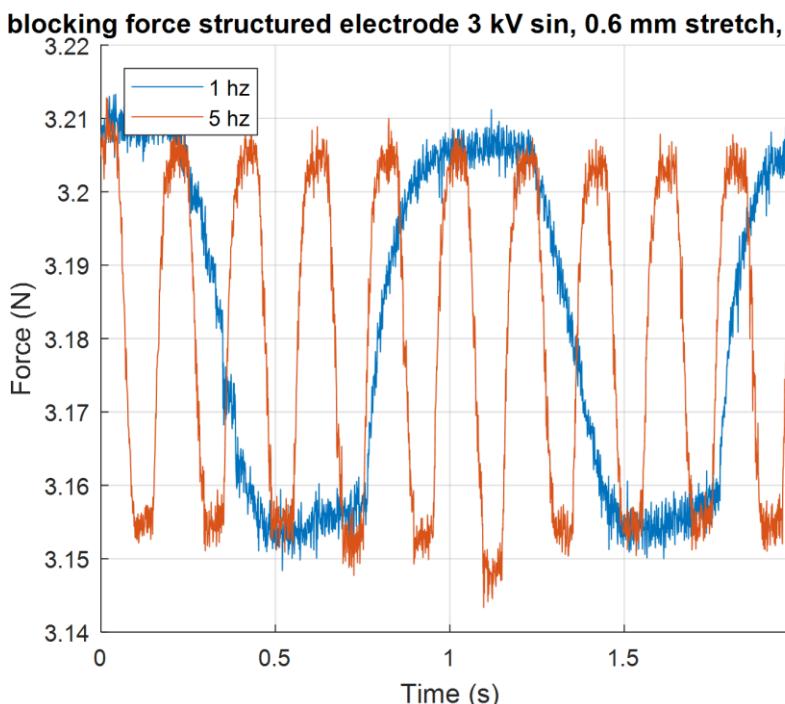
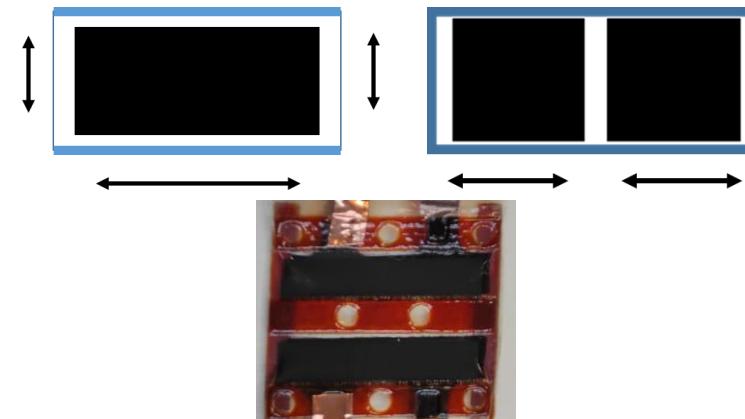
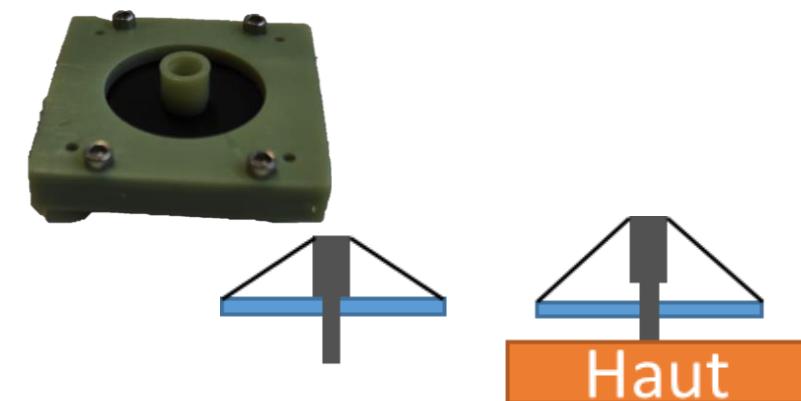
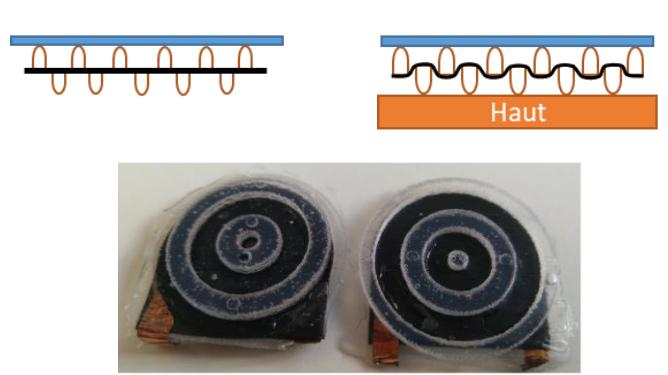


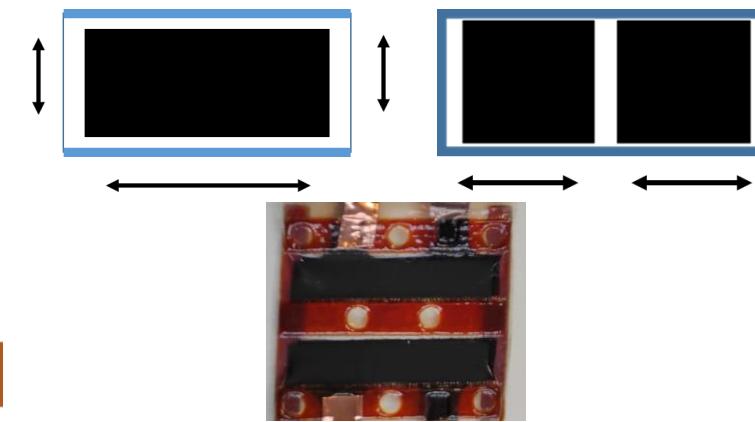
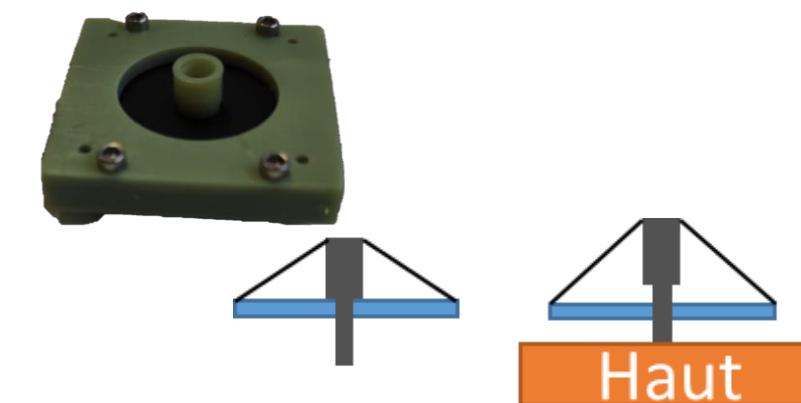
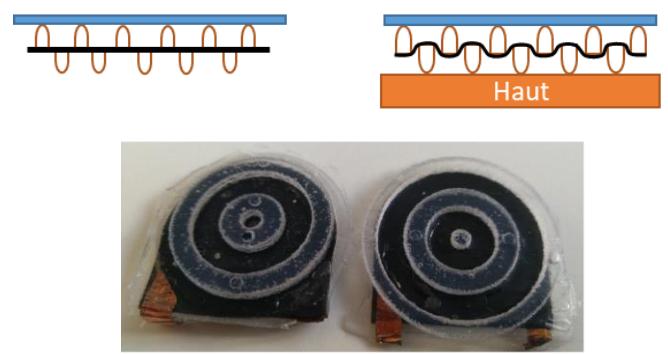




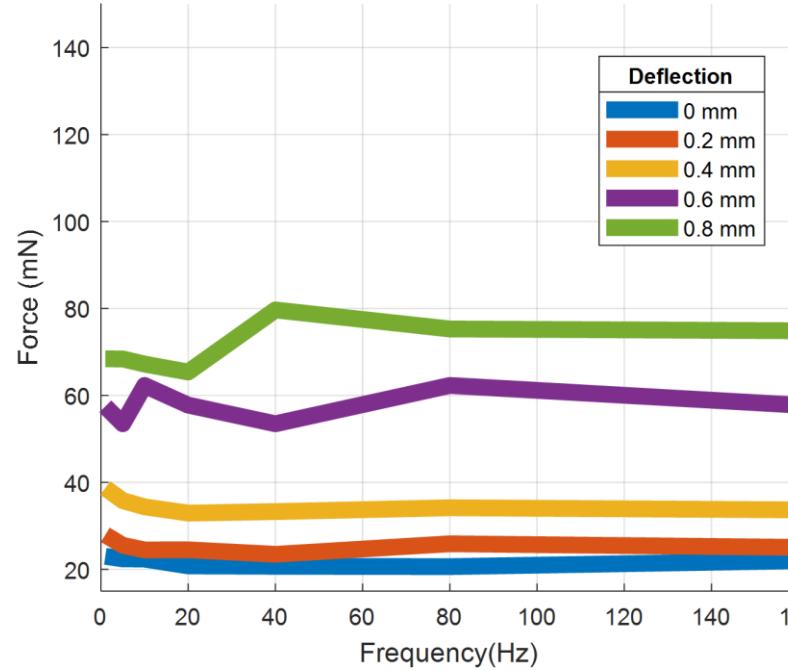


Geometrie / Messprinzip	Nr.	Beschreibung	Intensität	Komplexität	Flachbau
	7	Strukturierter DE (orth. Kraftwirkung)			
	8	DE mit vorgeformter Silikonschicht (orth. Kraftwirkung)			
	9	DE mit innerem Vorspannmech. (orth. Kraftwirkung)			
	10	Segmentierter DE (tang. und orth. Kraftwirkung)			
	11	Biegebalken mit DE (tang. und orth. Kraftwirkung)			
	12	Gegeneinander gespannte NBS (tang. Kraftwirkung)			
Geometrie / Messprinzip	Nr.	Beschreibung	Intensität	Komplexität	Flachbau
	1	DE Vorgespannt (orth. Kraftwirkung)	●	●	●
	2	DE mit NBS (orth. Kraftwirkung)	●	●	●
	3	PET / Silikon Dom als Vorspannmech. (orth. Kraftwirkung)	●	●	●
	4	NBS und DE in Balkenrichtung (tang. Kraftwirkung)	●	●	●
	5	Siehe 4 aber NBS in Ebene (tang. Kraftwirkung)	●	●	●
	6	2 NBs in Ebene (tang. Kraftwirkung)	●	●	●

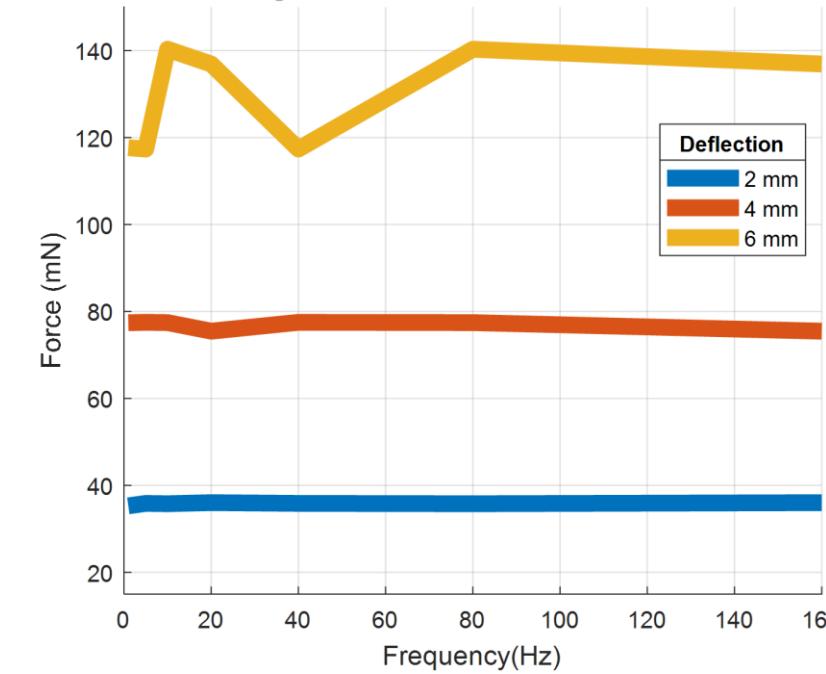




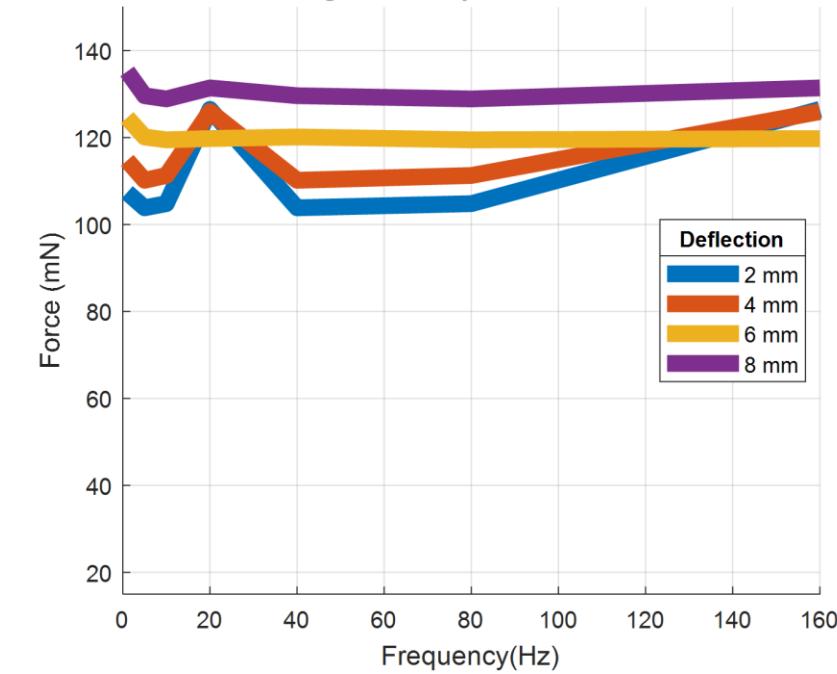
blocking force structured electrode 3 kV sin

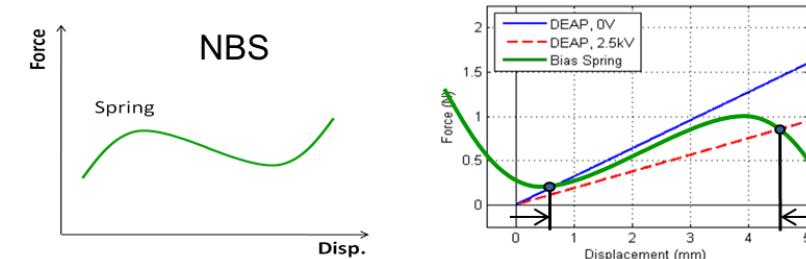
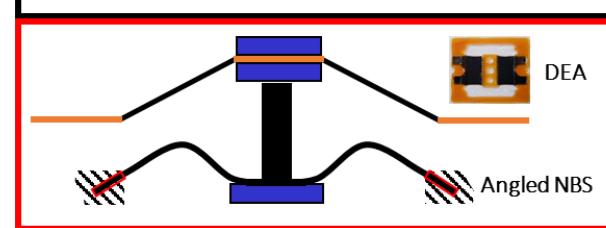
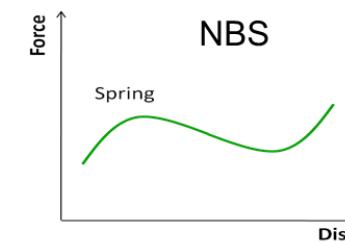
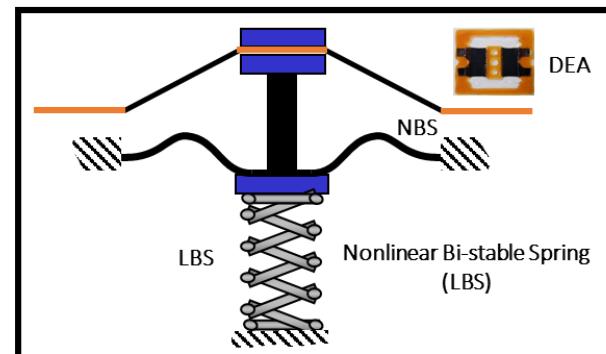
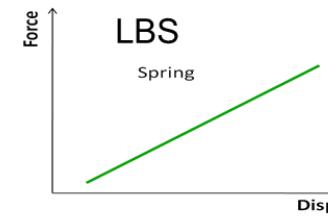
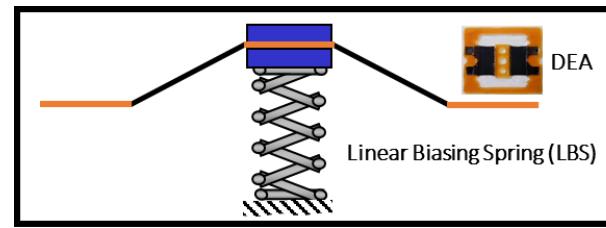


blocking force 20mm round electrode 3 kV sin

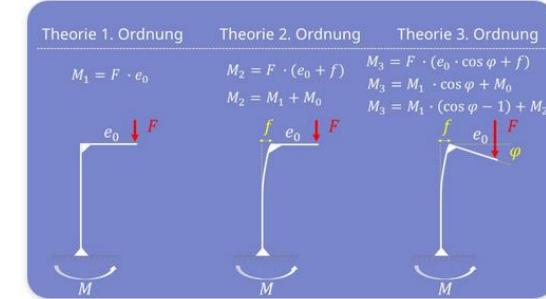


blocking force strip electrode 3 kV sin

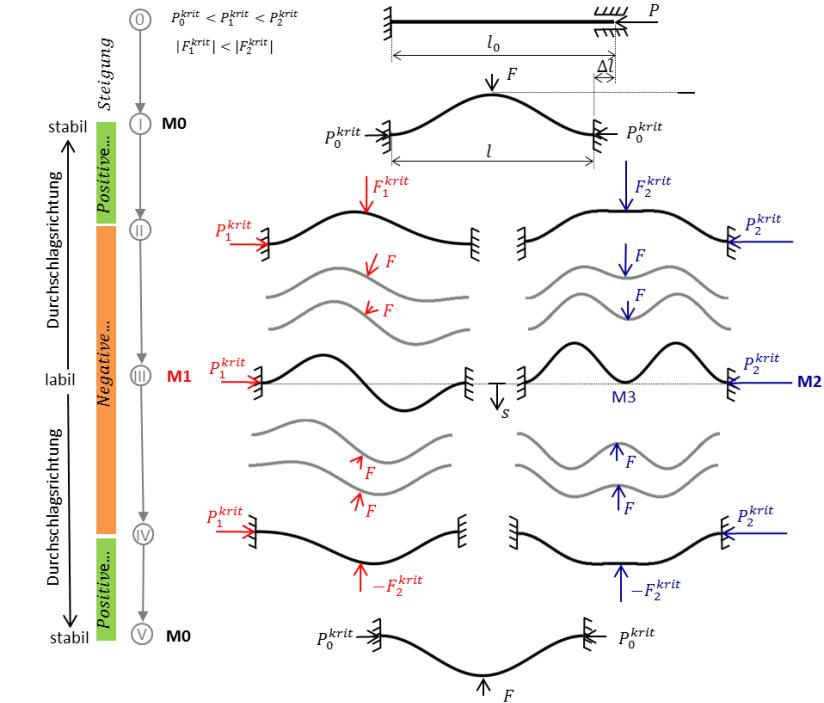




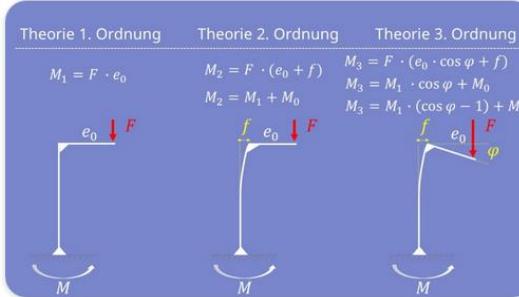
Beam theory for NBS calculation



Bending deformation of fixed end beams



Beam theory for NBS calculation



Euler beam equation

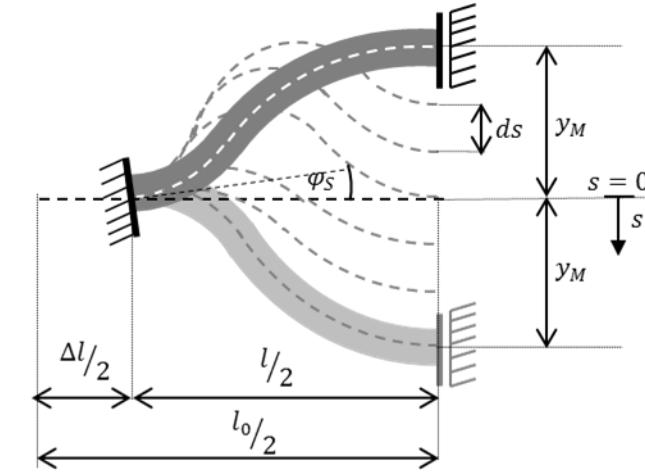
$$\frac{d^4}{dx^4} \omega(x) + \lambda^2 \frac{d^2}{dx^2} \omega(x) = 0 \quad \text{with} \quad \lambda^2 = \frac{P}{E_B I_y}.$$

Euler beam – extension acc. Vangbo et al.

$$F(\eta) = \frac{-4(\eta l)^2 E_B I_y}{l^3 \sqrt{3 - \frac{12}{\eta l} \tan\left(\frac{\eta l}{4}\right) + \tan^2\left(\frac{\eta l}{4}\right)}} \sqrt{(\Delta l - \Delta l_p(\eta))l}$$

$$s(\eta) = -\frac{l^3 F(\eta)}{(\eta l)^2 E_B I_y} \left[\frac{1}{4} - \frac{1}{\eta l} \tan\left(\frac{\eta l}{4}\right) \right] \quad \eta^2 = \frac{P}{E_B I_y}.$$

FE Simulation

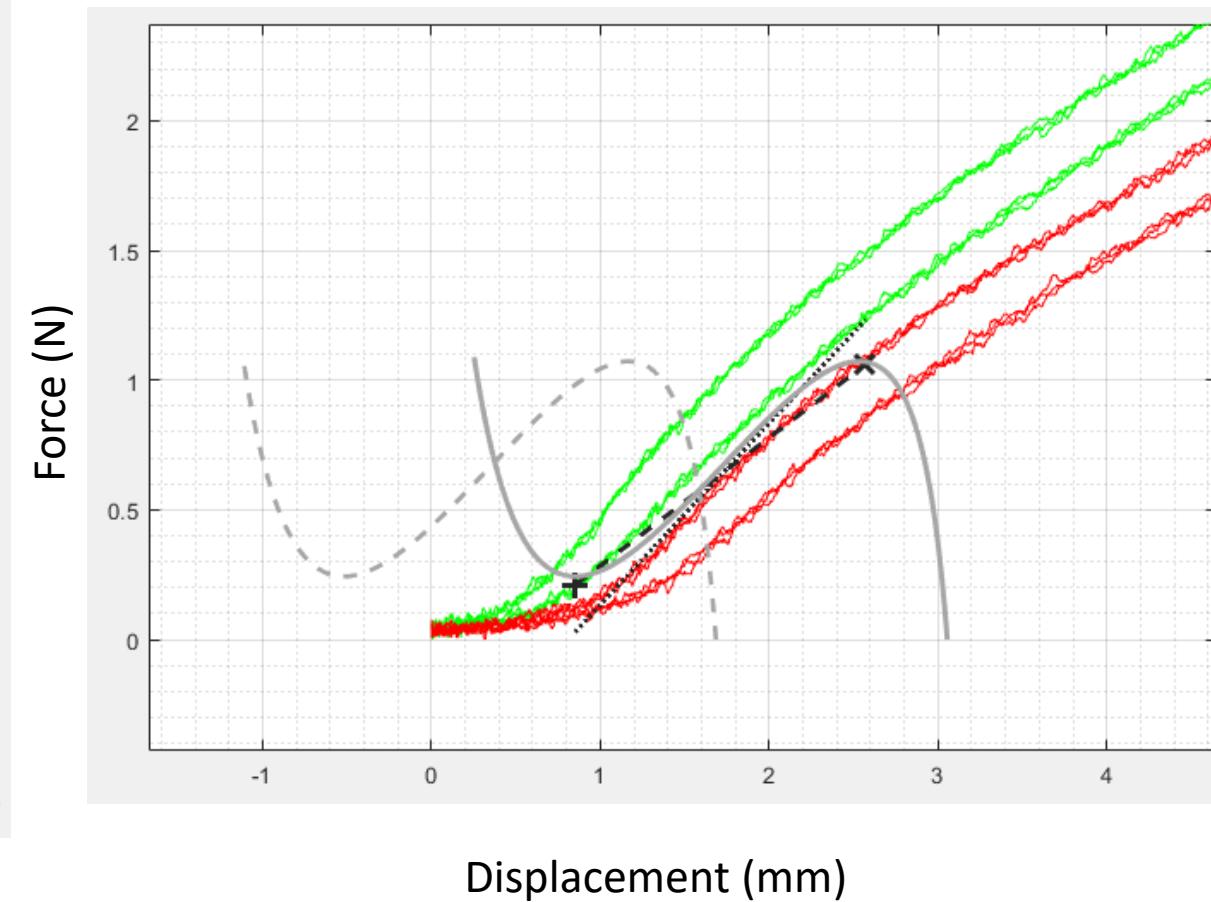
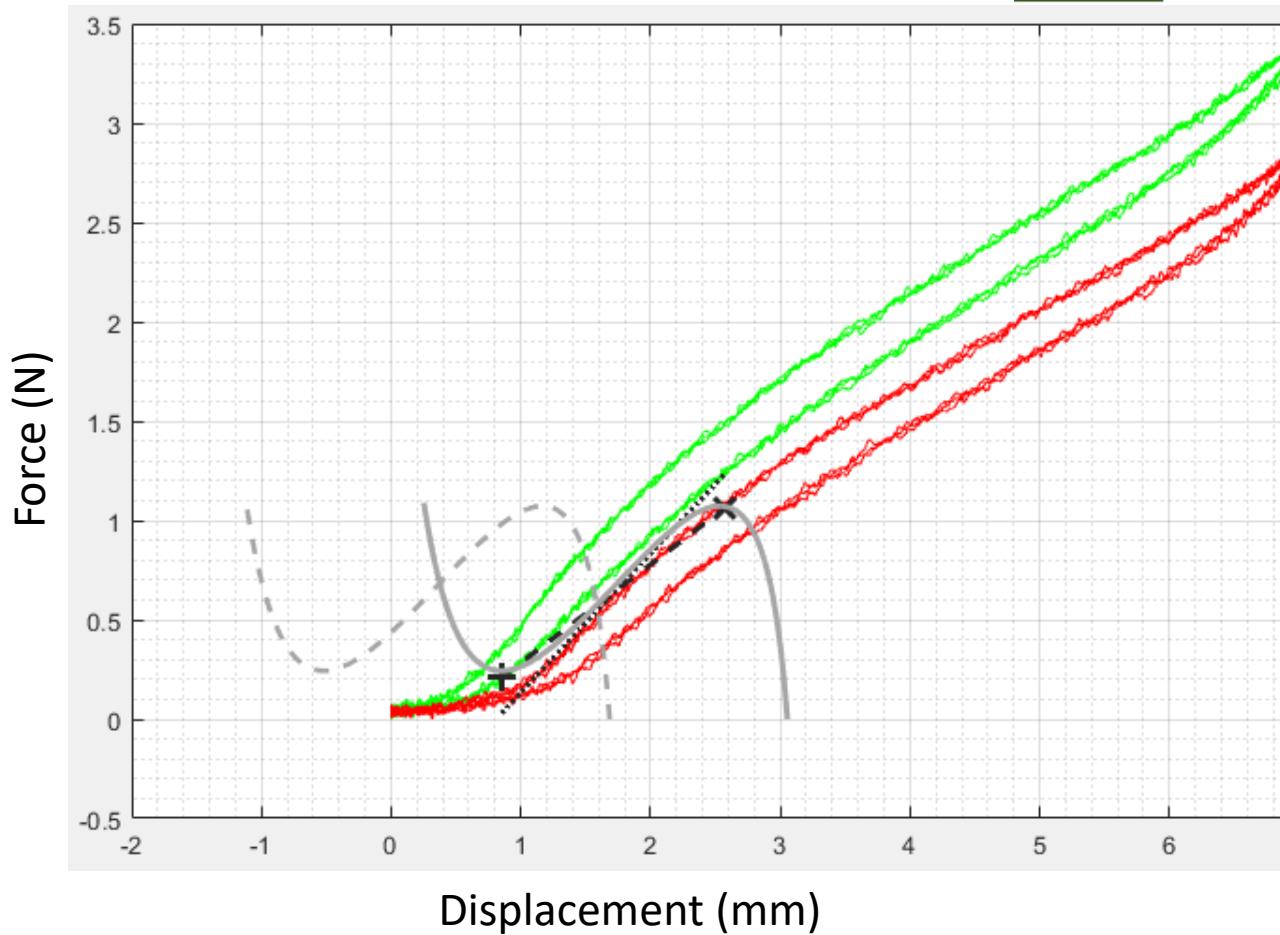
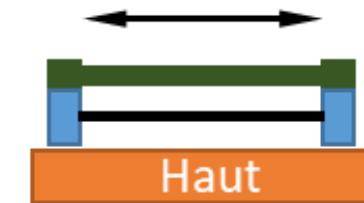


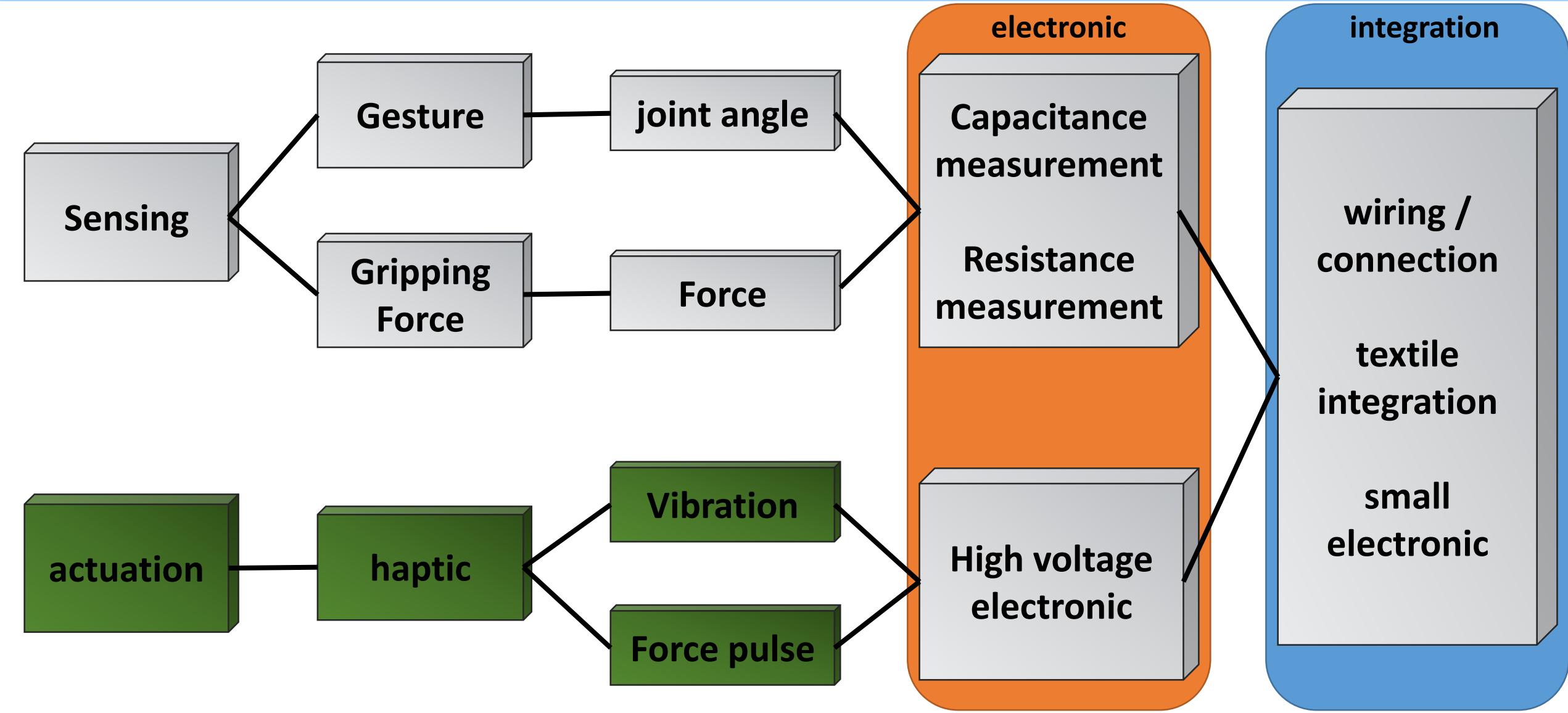
$$\text{Compression: } c = \frac{l_0 - \Delta l}{l_0} = \frac{l}{l_0}$$

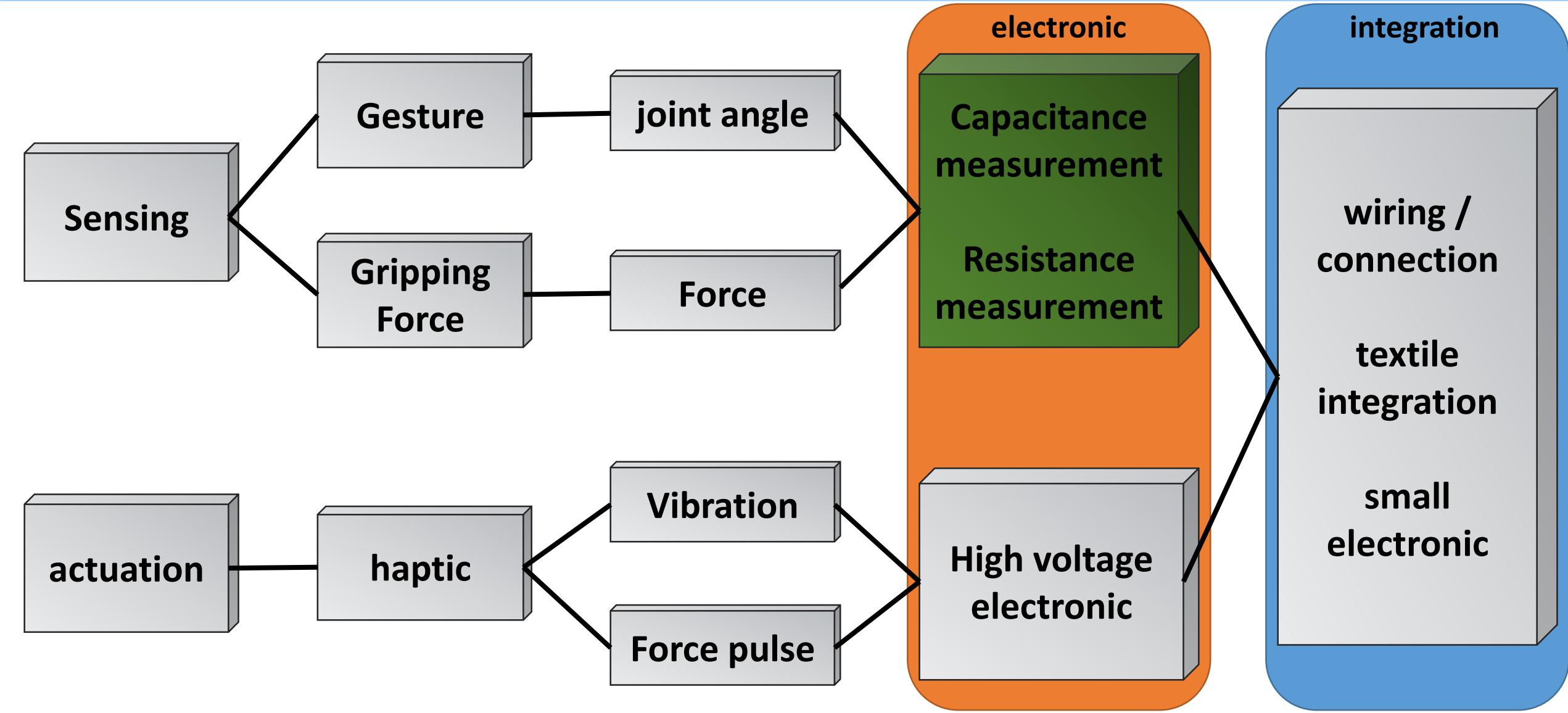
Natural Angle: ϕ_N

Setting Angle: ϕ_S

Stroke – Increment: ds

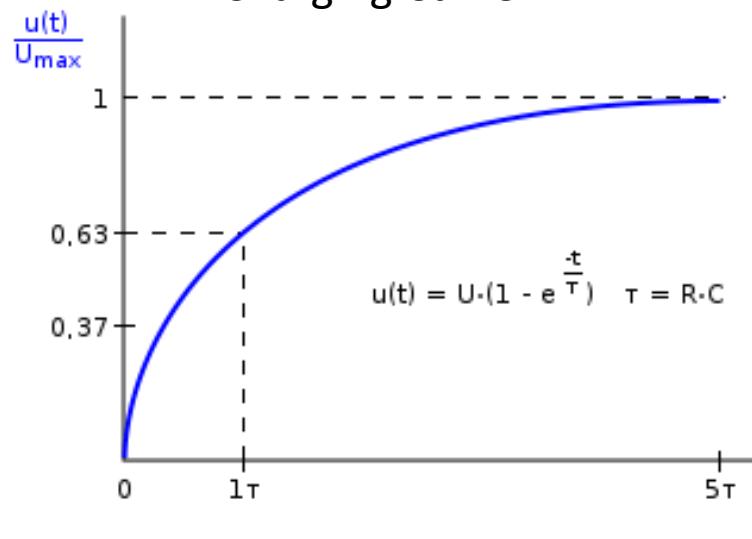




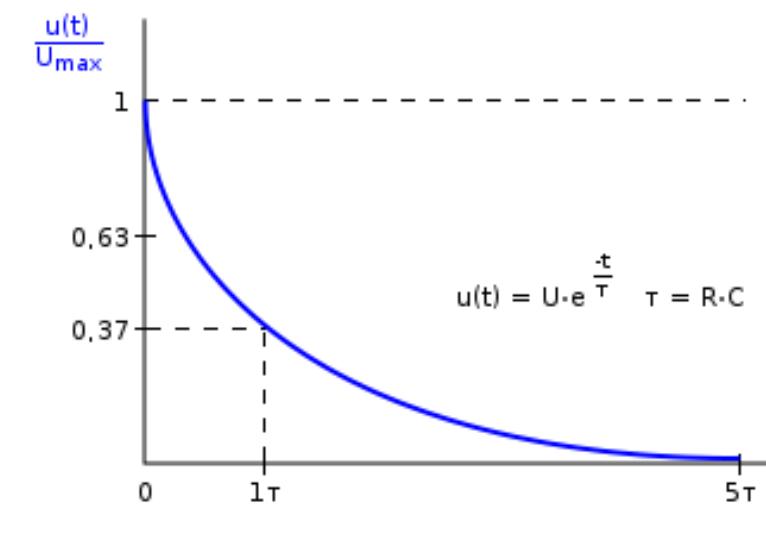




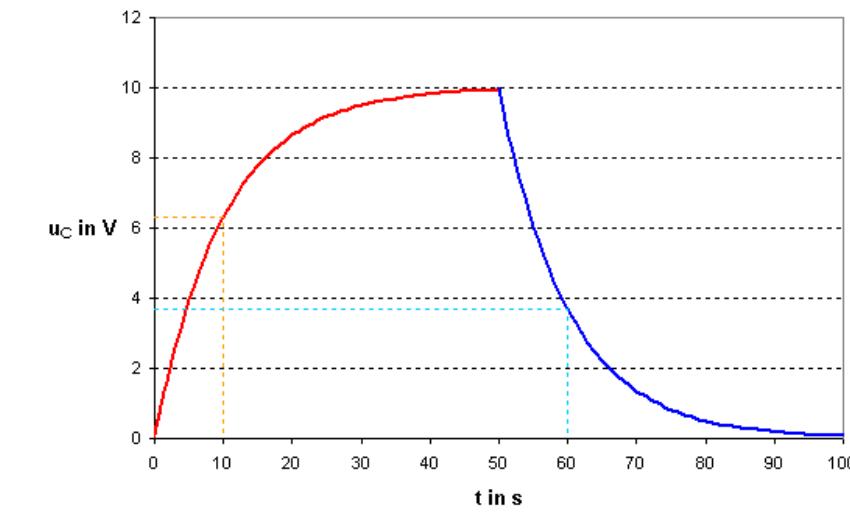
Charging Curve



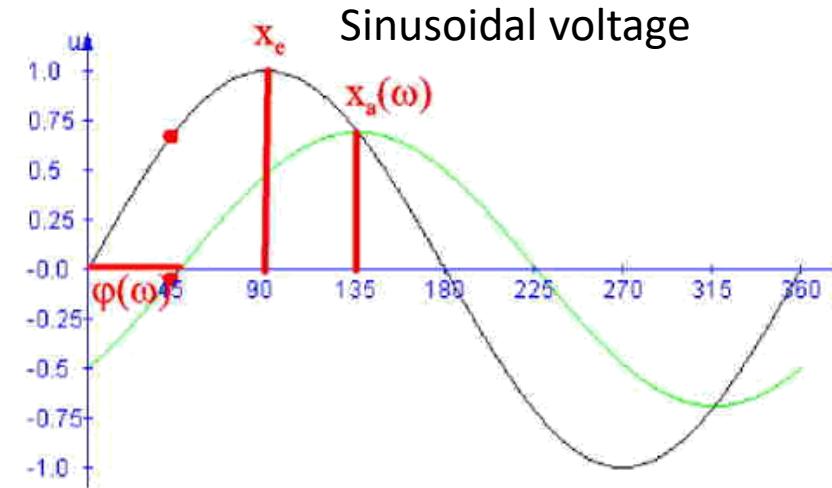
Discharging Curve



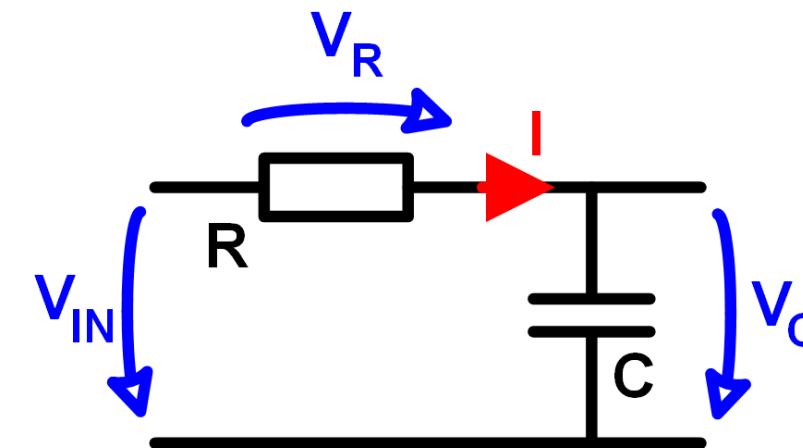
combination



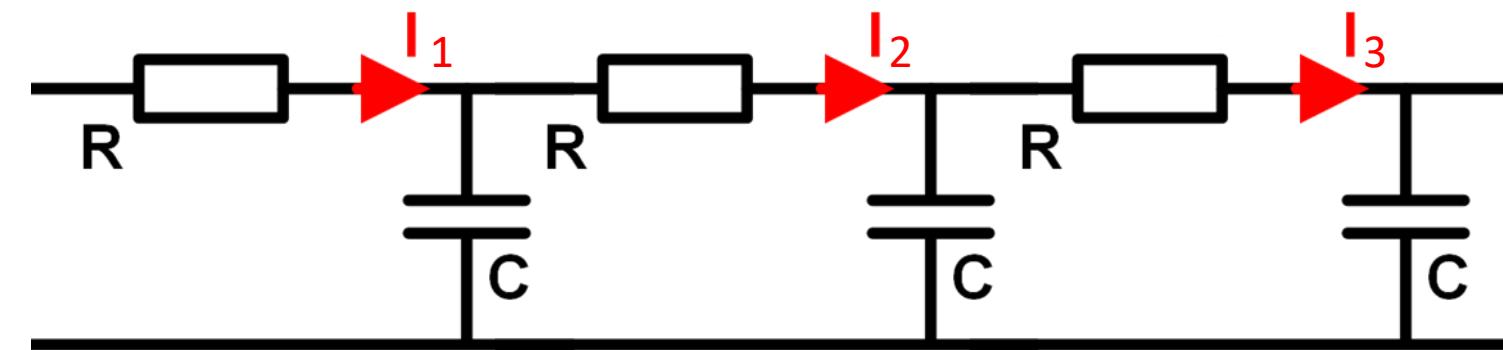
Sinusoidal voltage



Real Capacitor



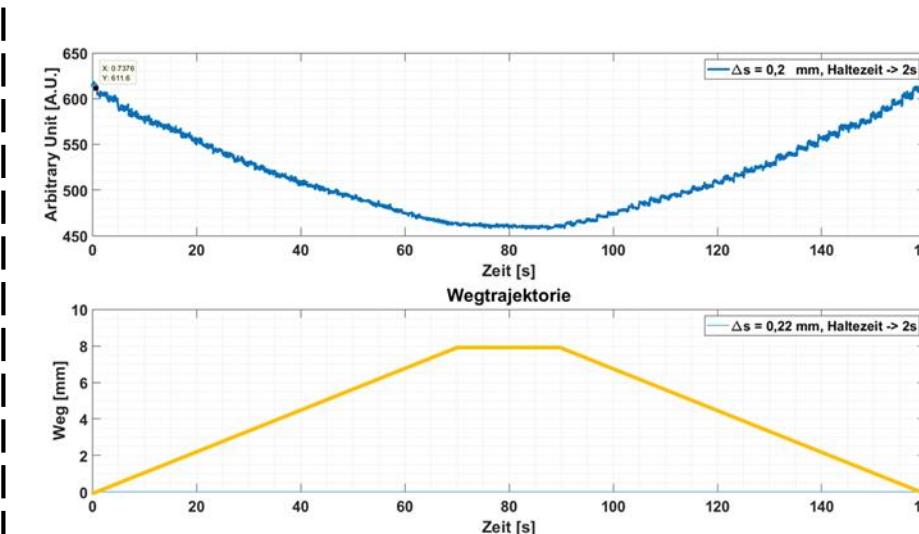
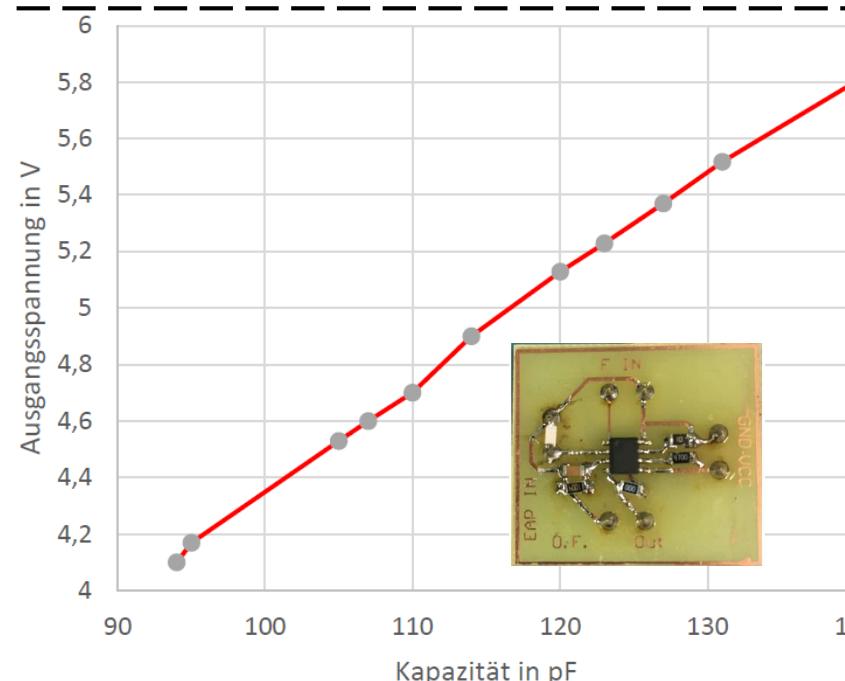
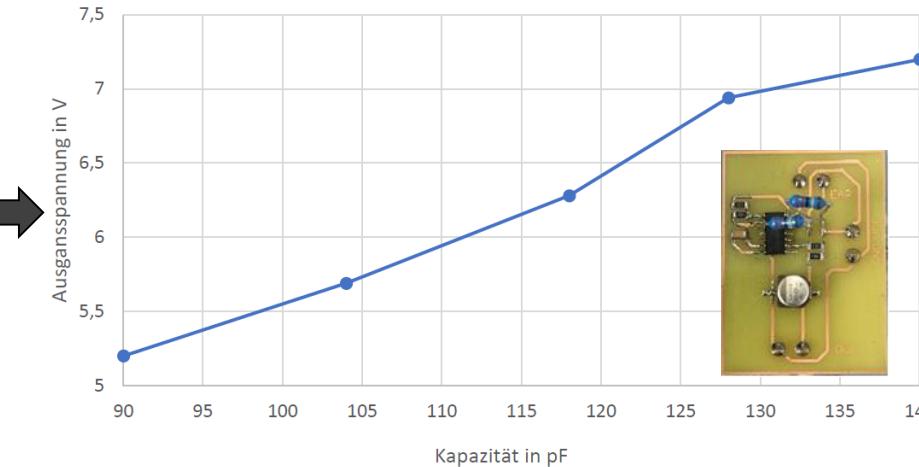
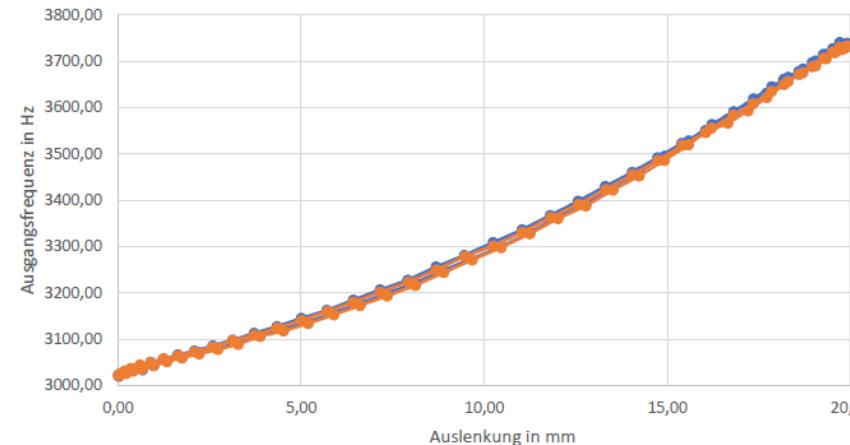
DE

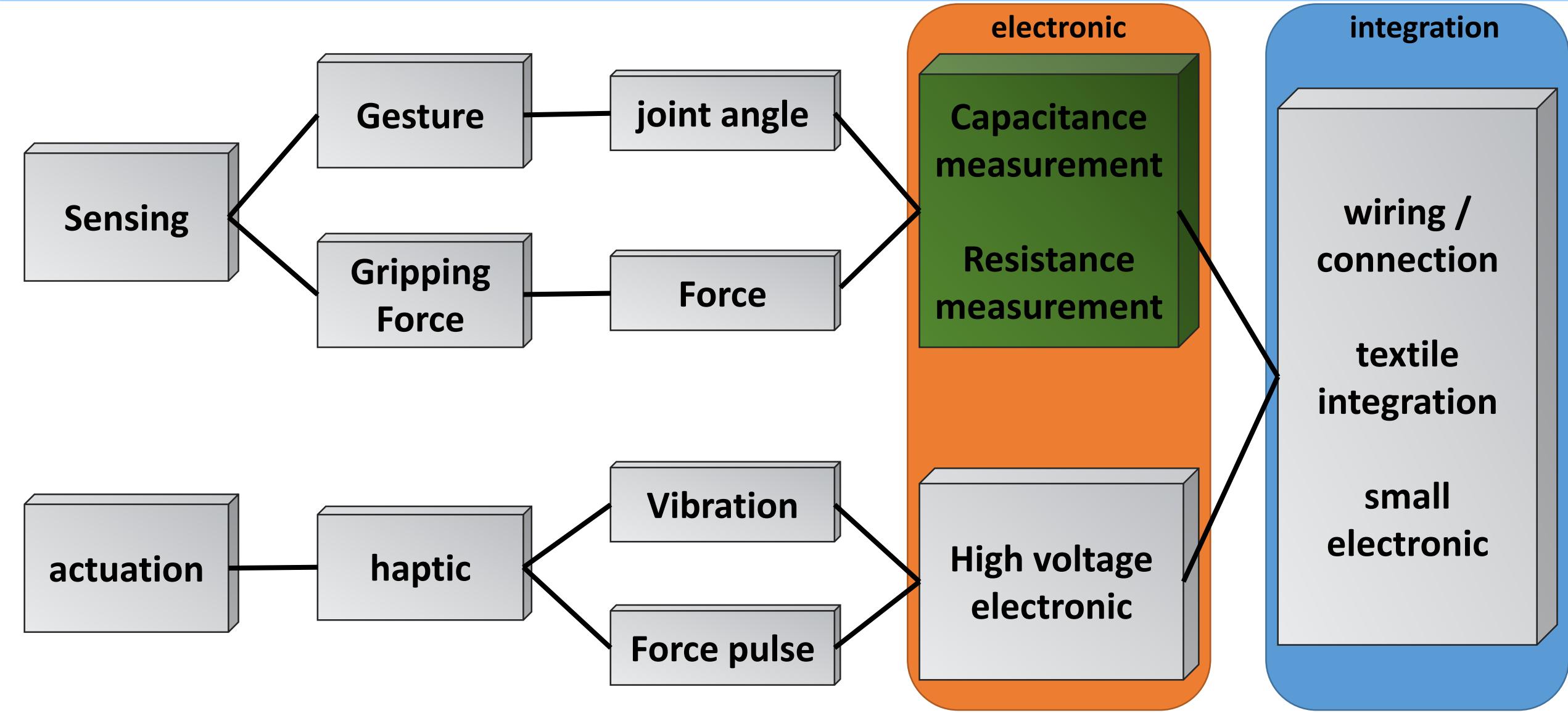


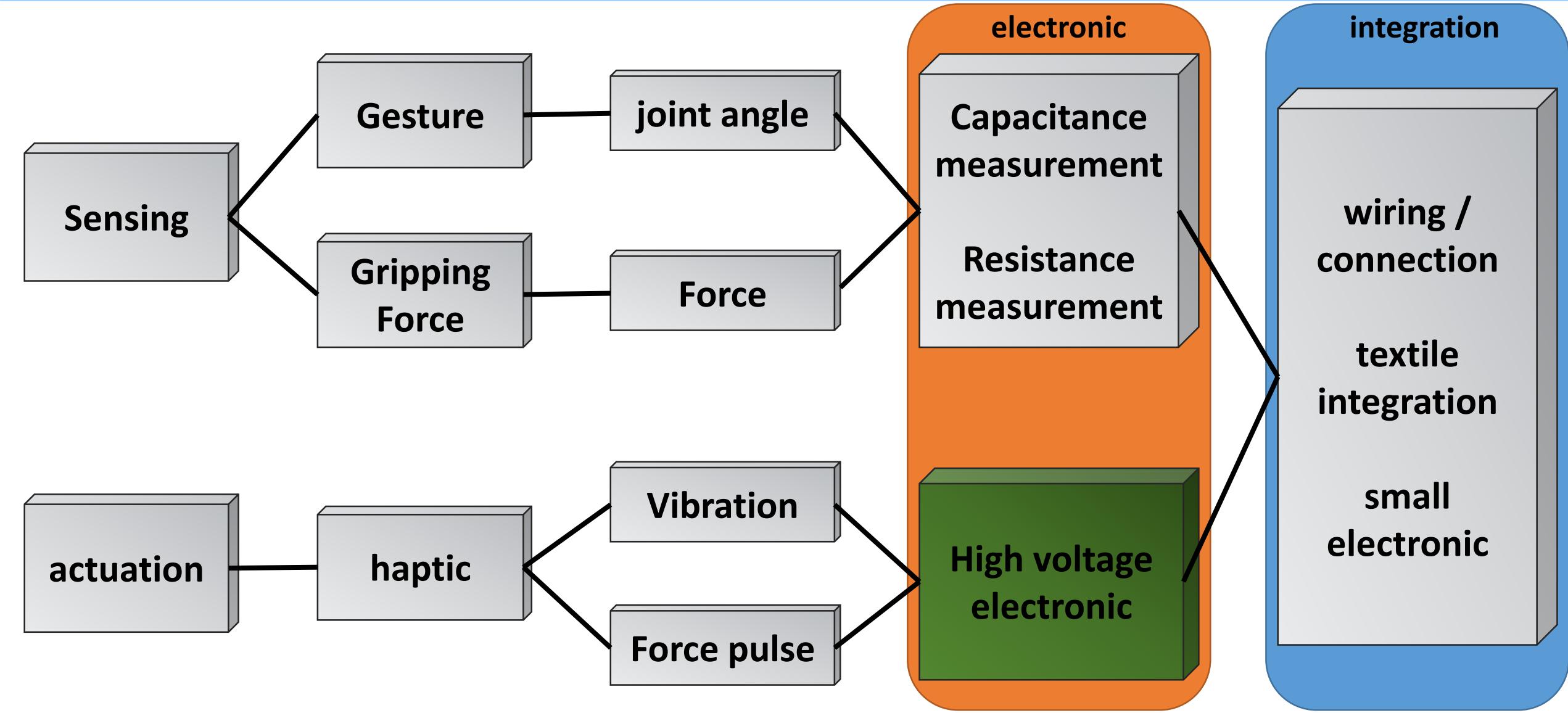
- 1 Resistance and 1 Capacity
- Relative low Resistance

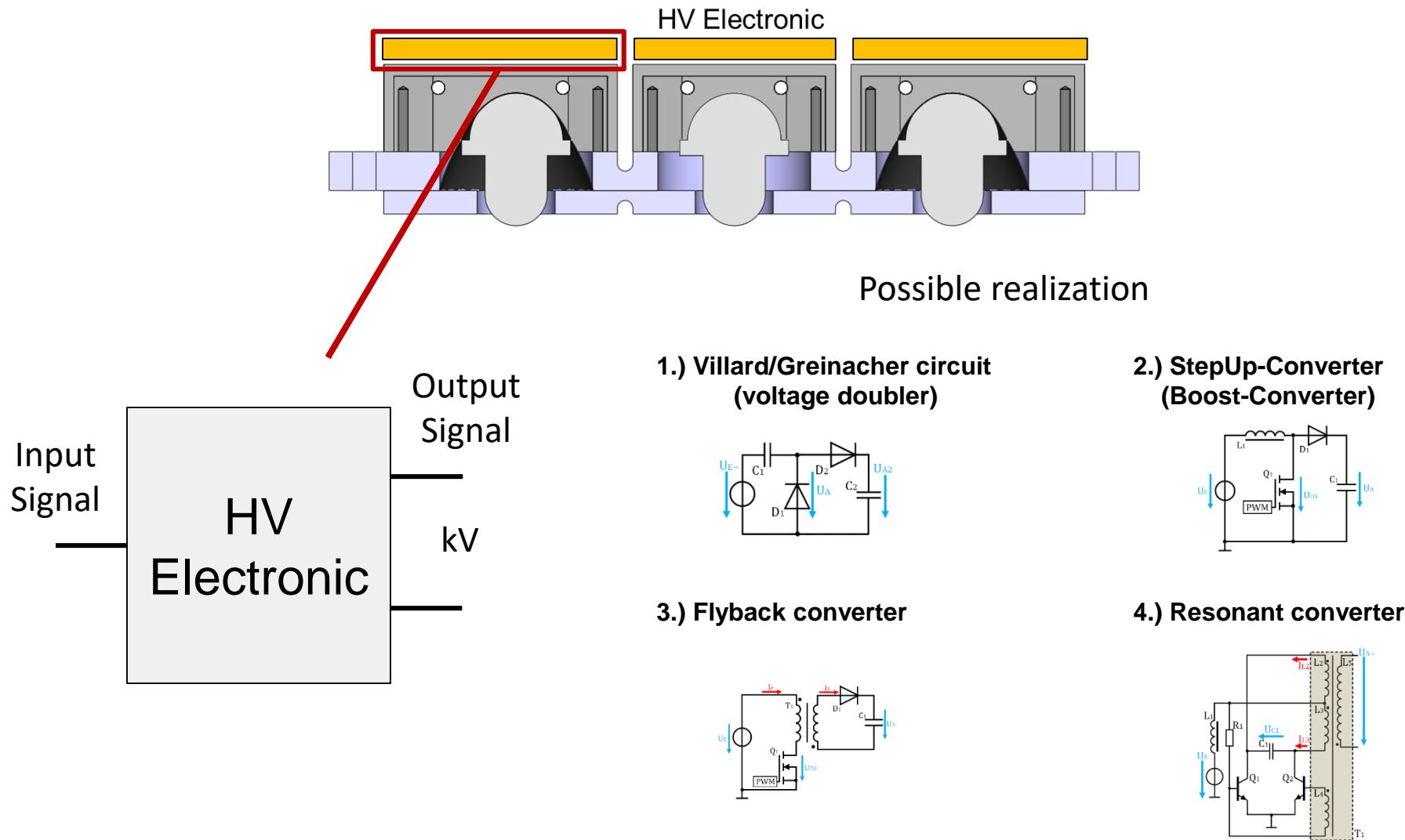
- more Resistances, more Capacities
- Relative high Resistance

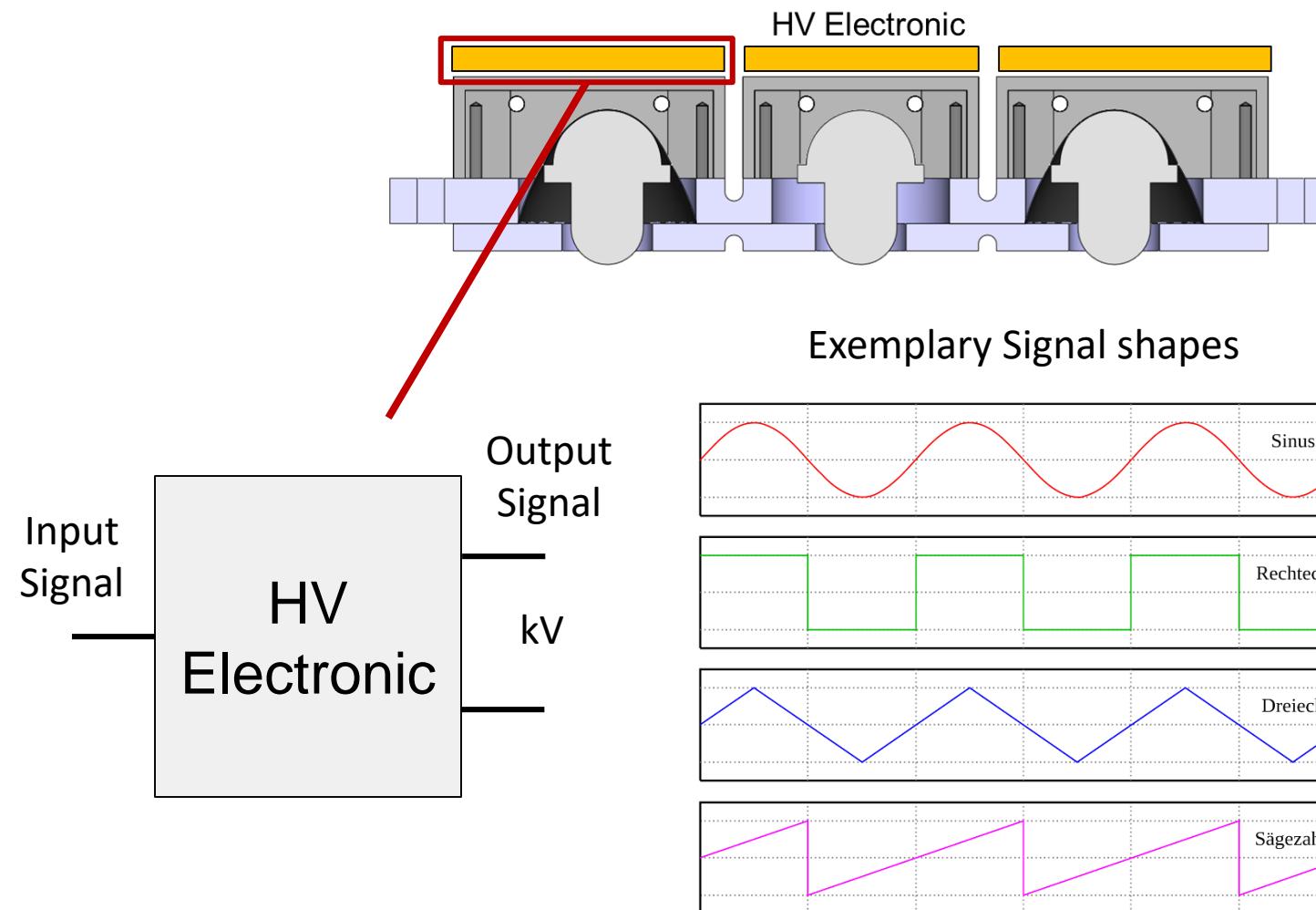
Difficult to measure the capacitance with the standard measurement circuits

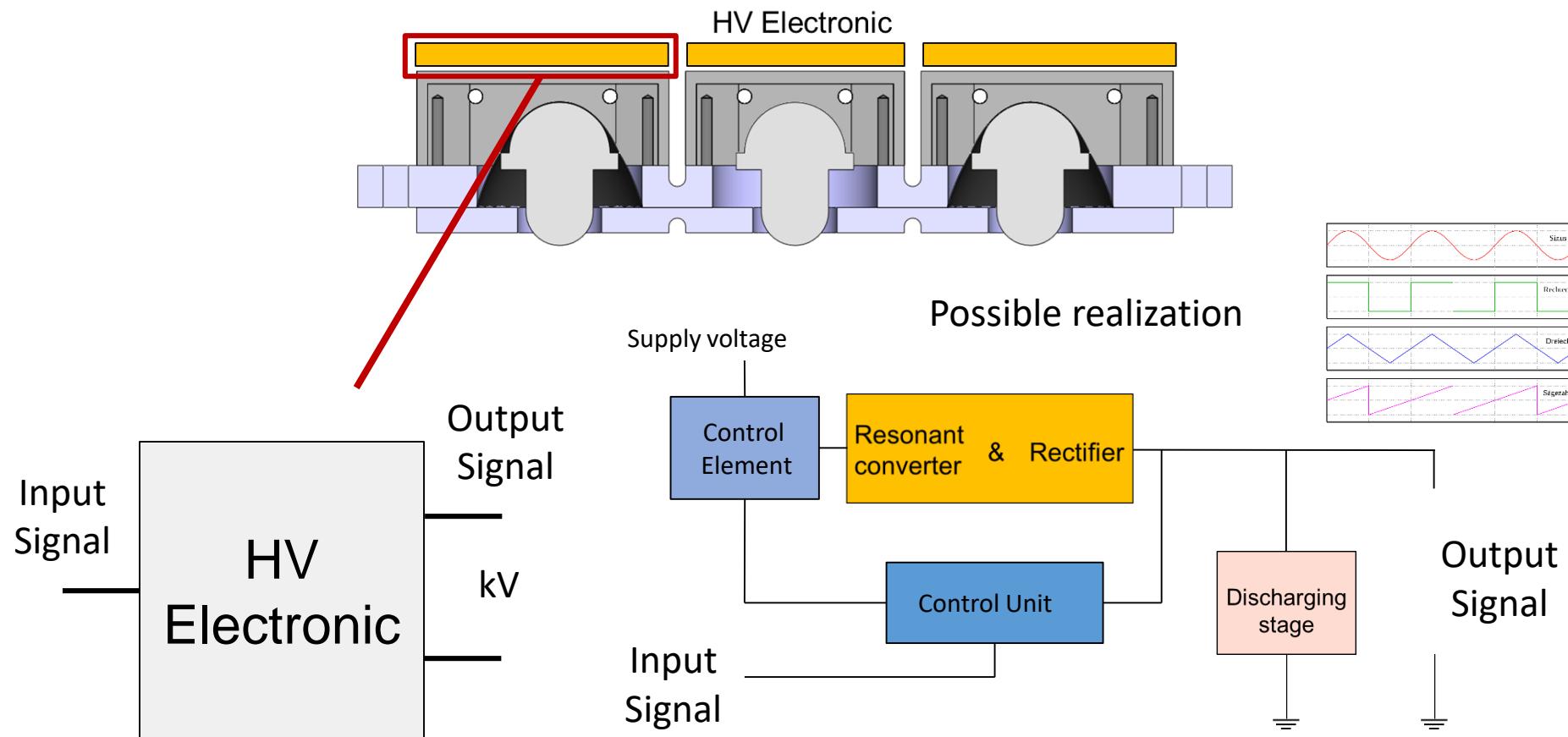




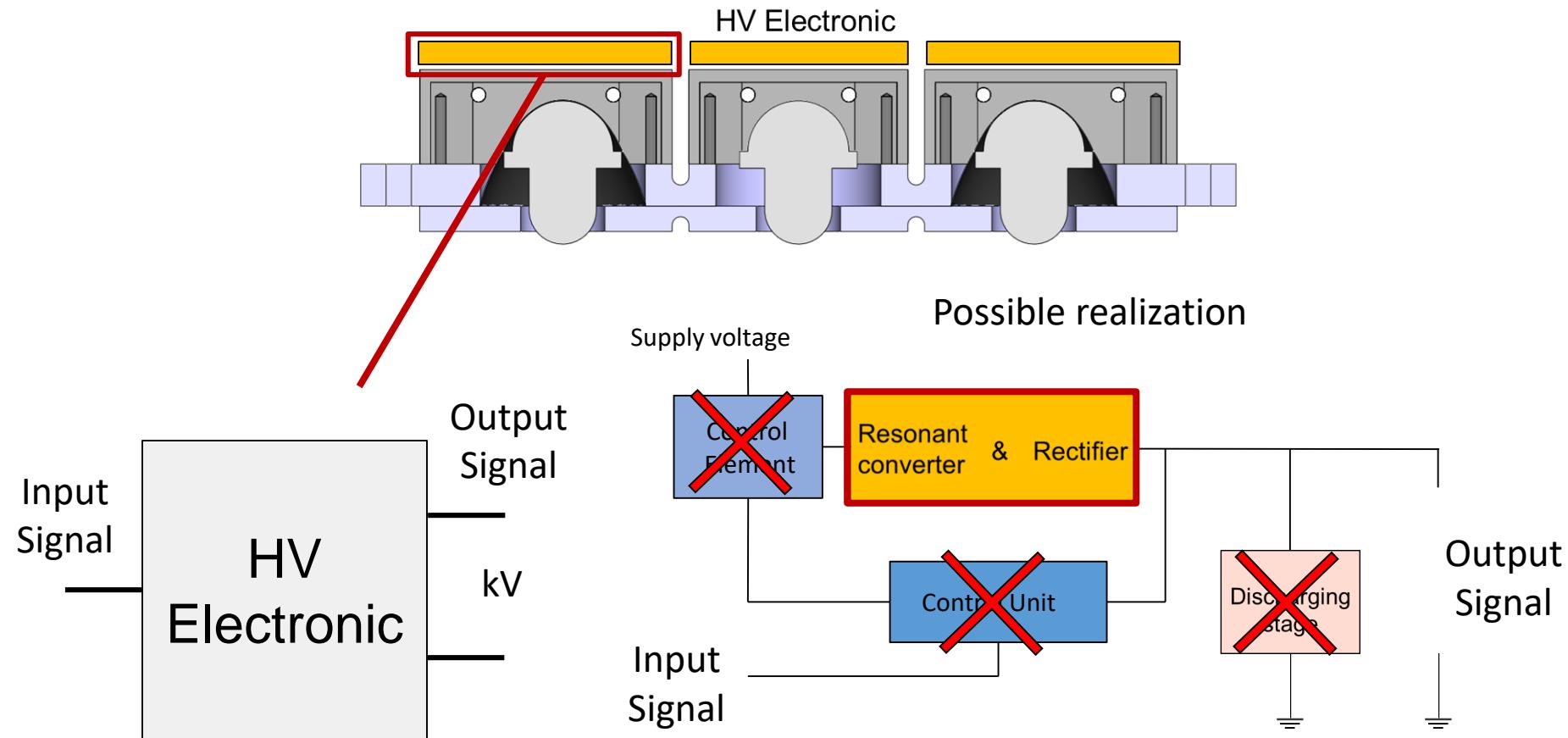




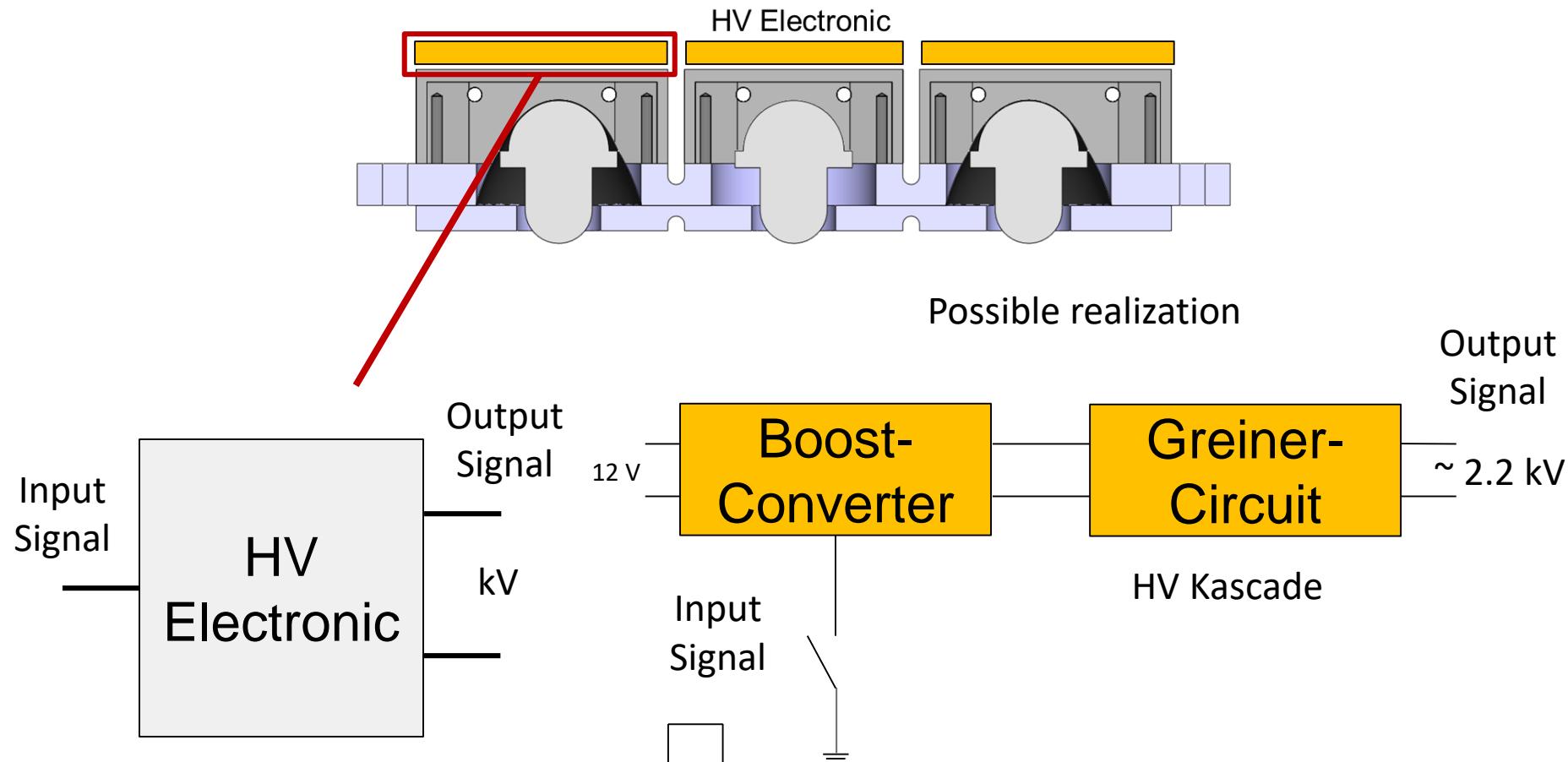




Relative complex circuit → big size of the circuit



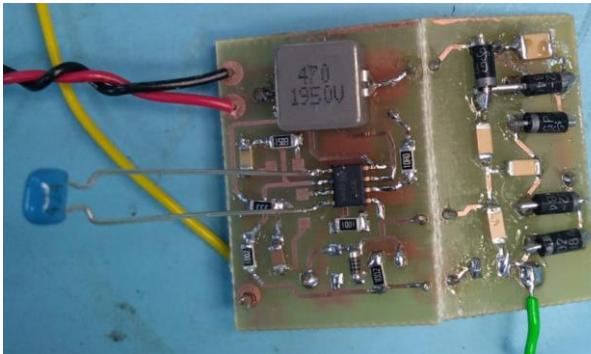
OR



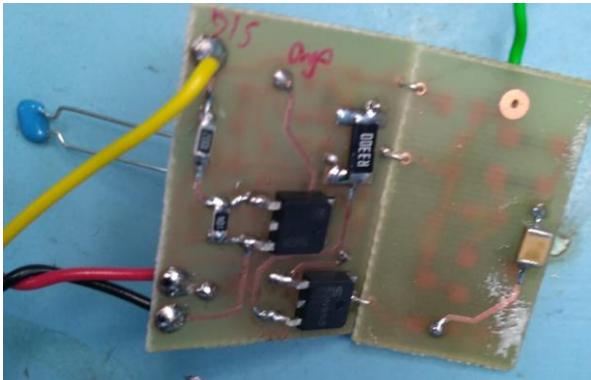
Relative simple circuit, small size of the circuit, rectangular or Peak Shape



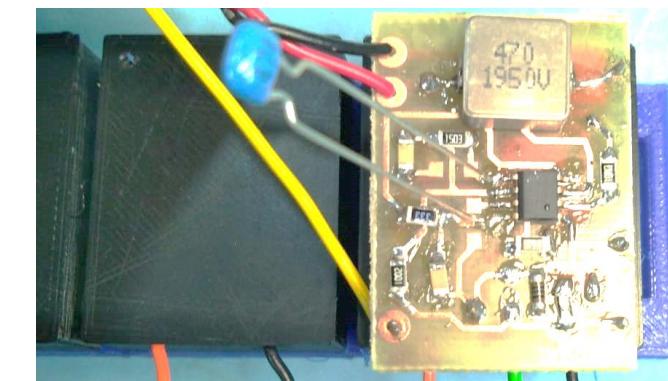
front side

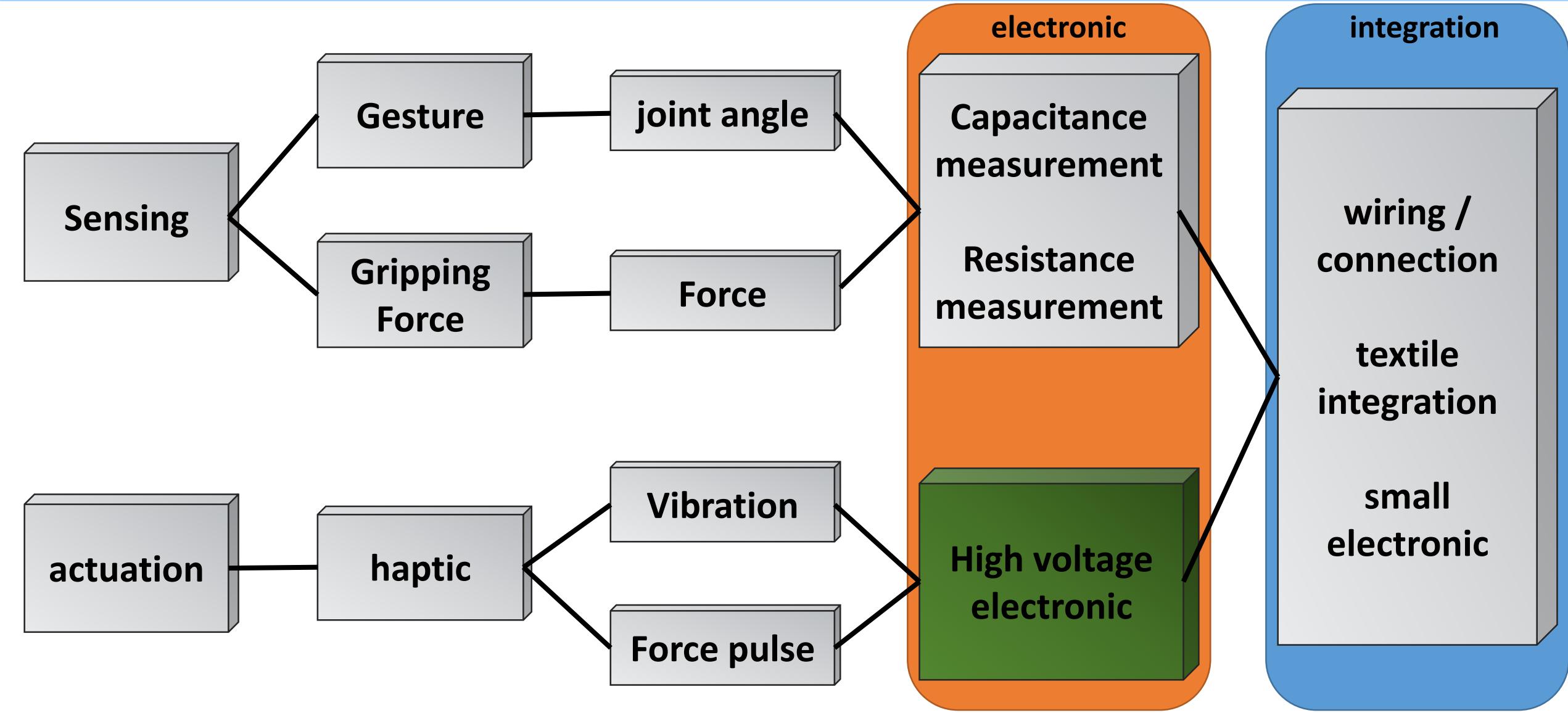


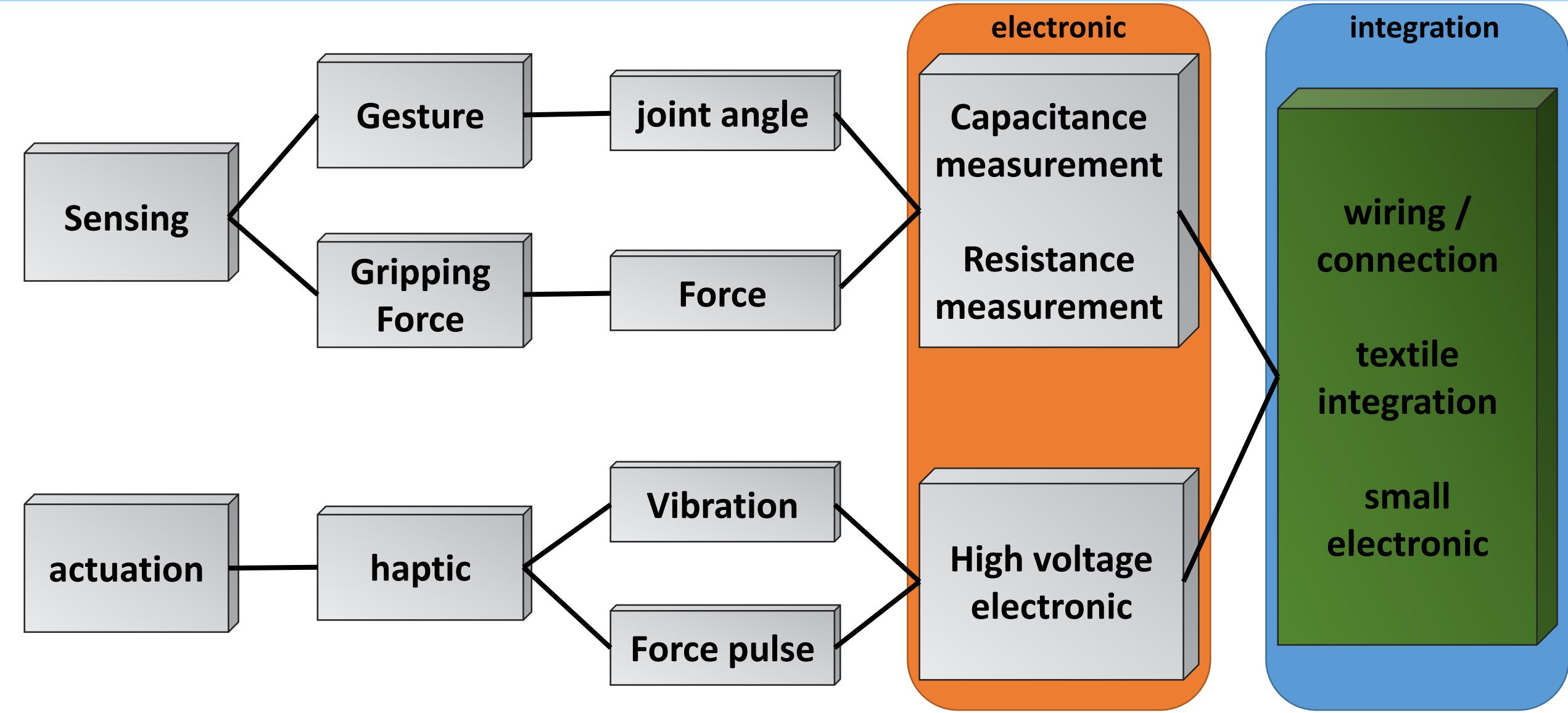
back side

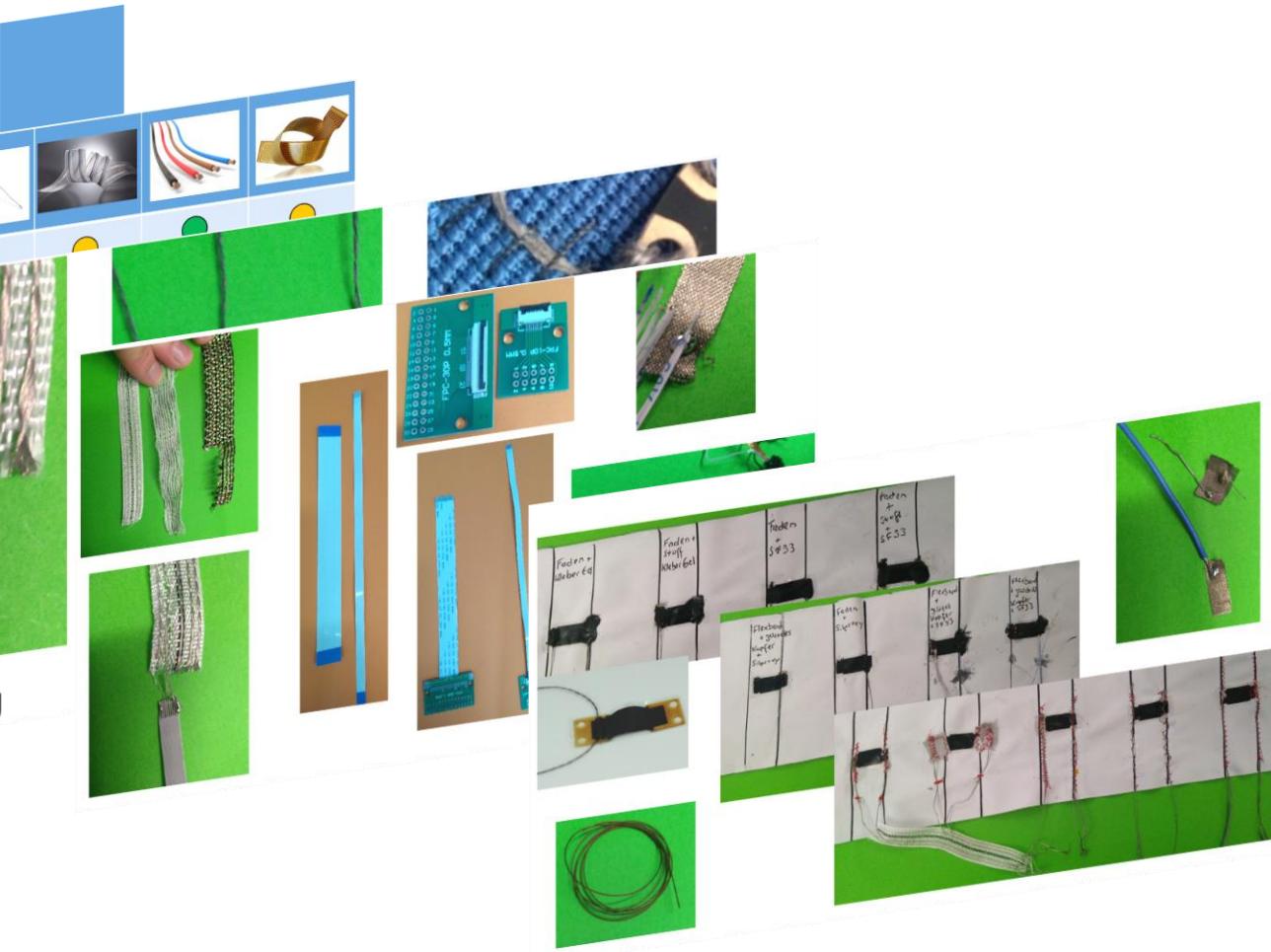


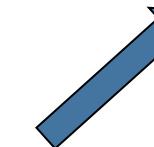
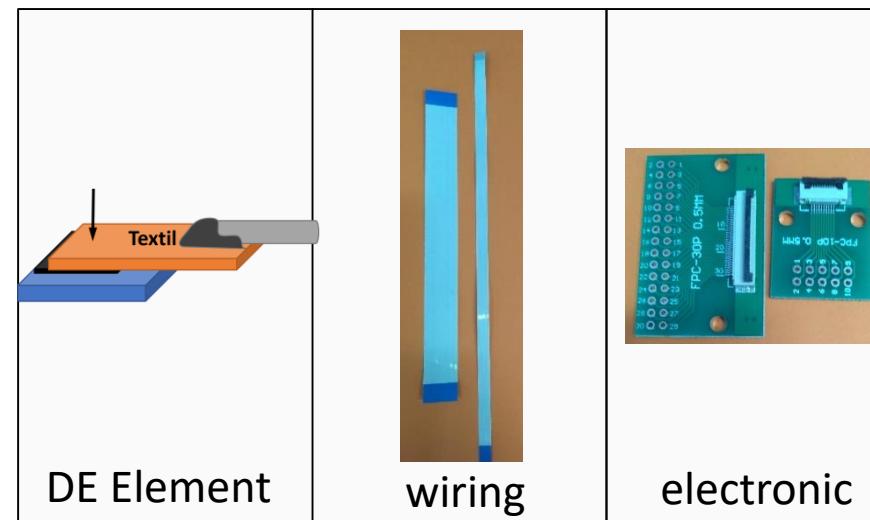
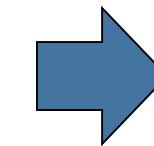
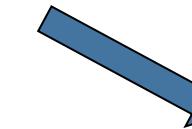
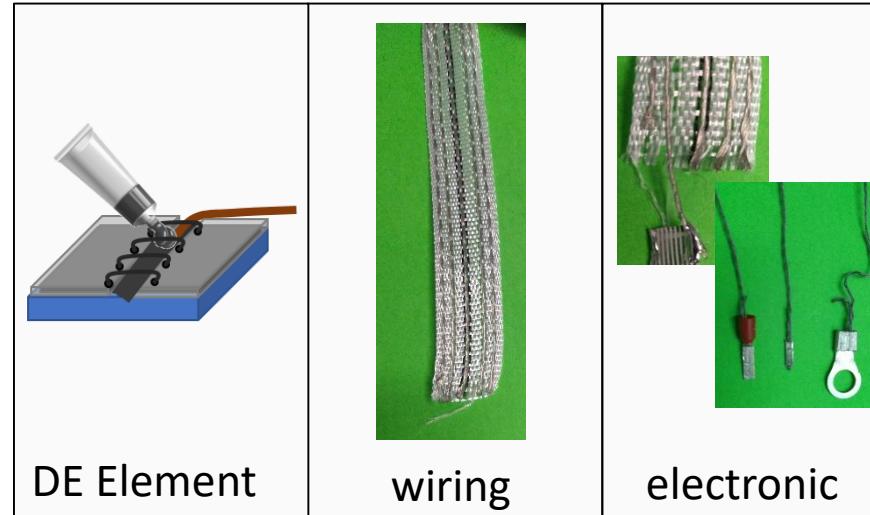
collapsible





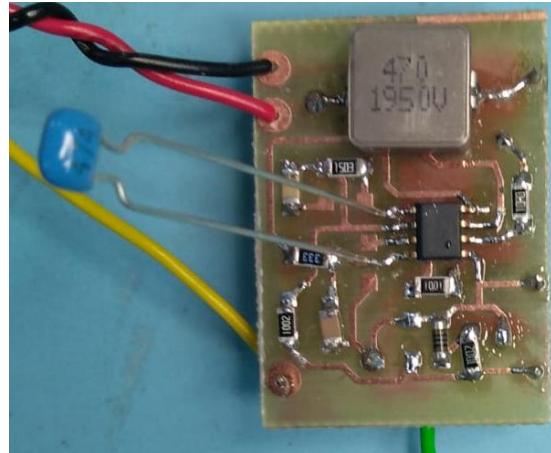
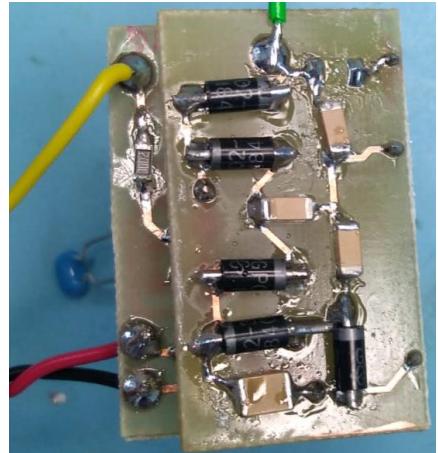




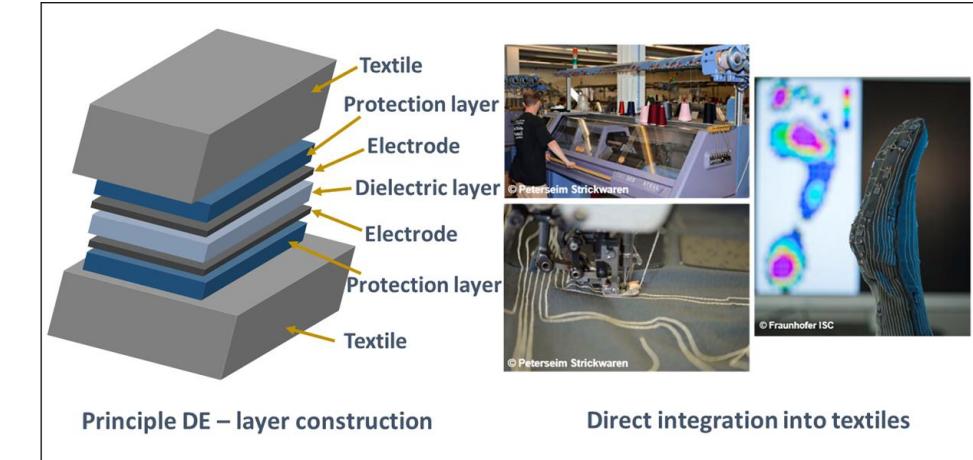




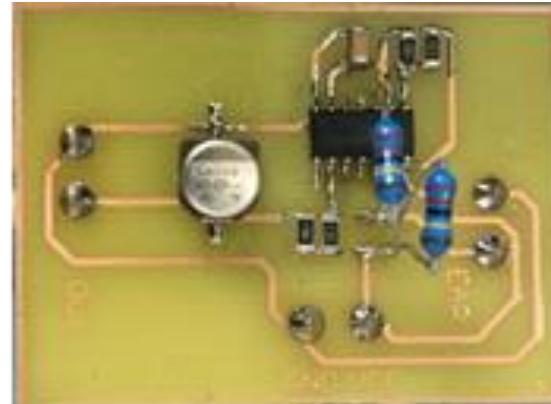
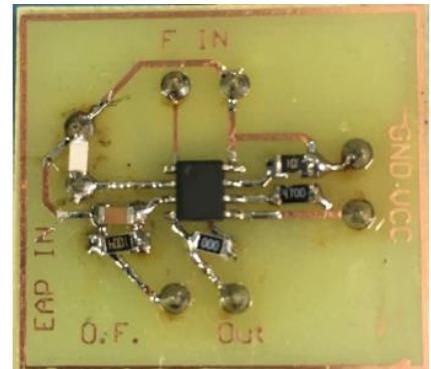
High voltage electronic



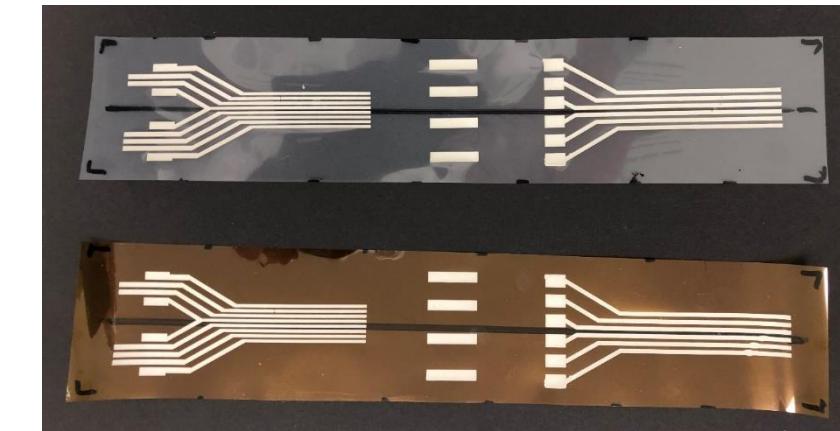
Integration into textiles



Capacitance measurement electronic



Connection to electronic





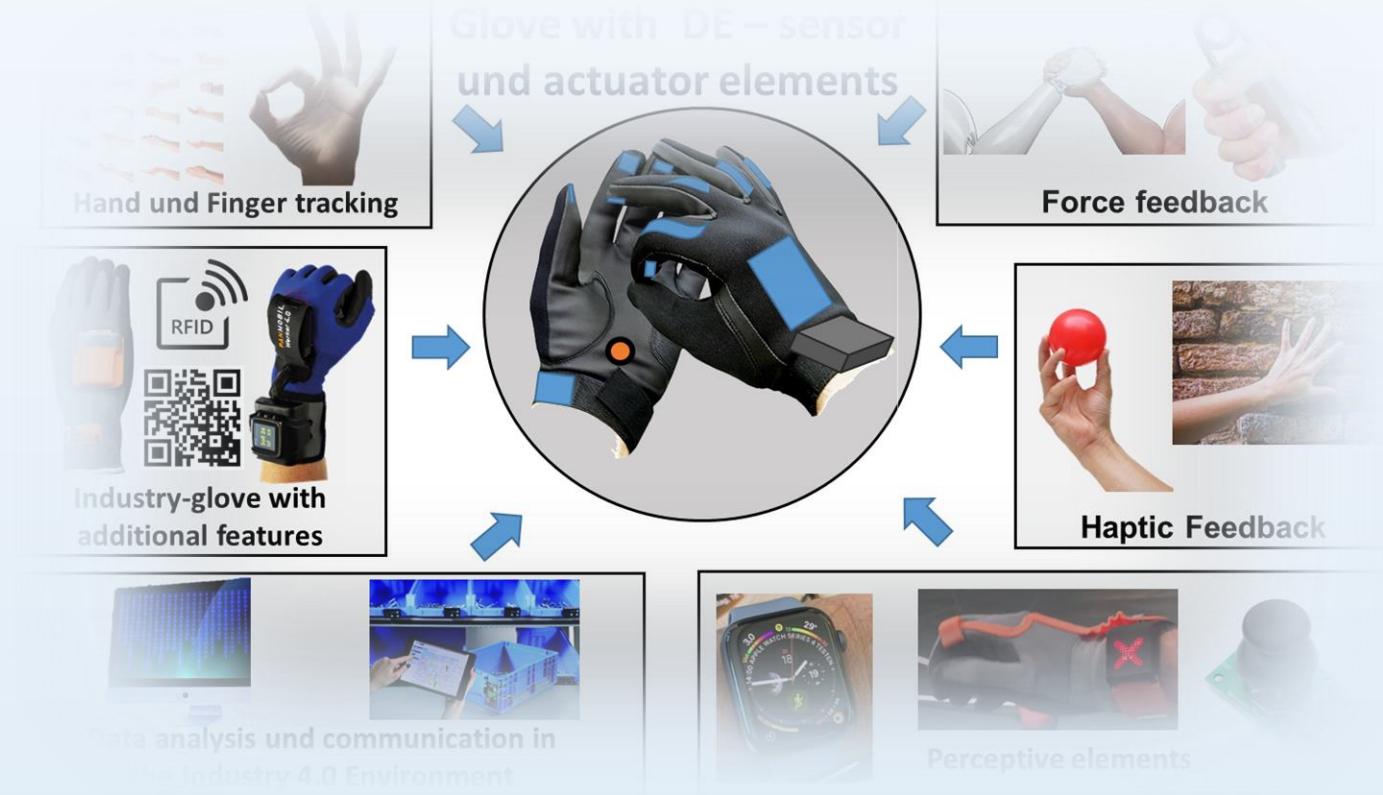
Structure of the assistance tool

- sensor
- actuator
- electronic
- integration

Prototype assembly

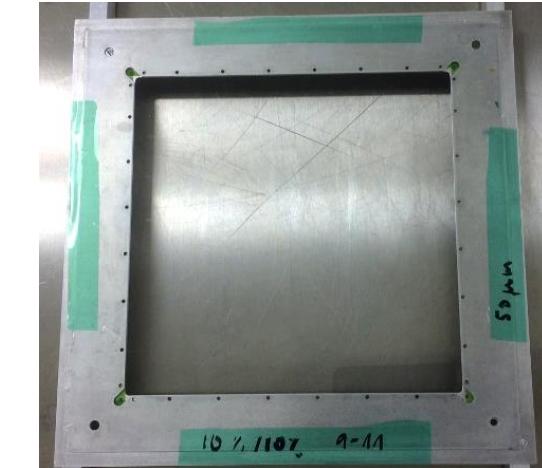
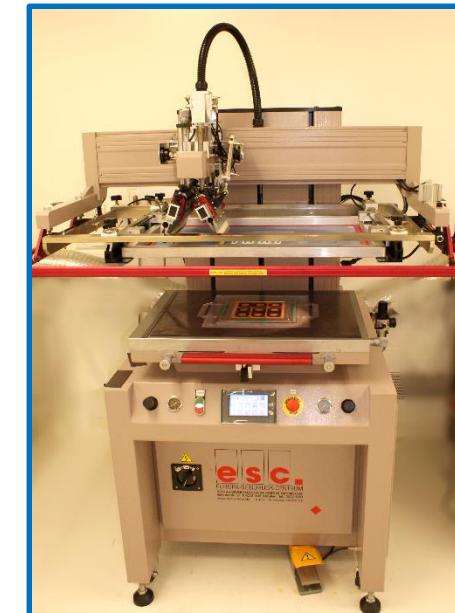
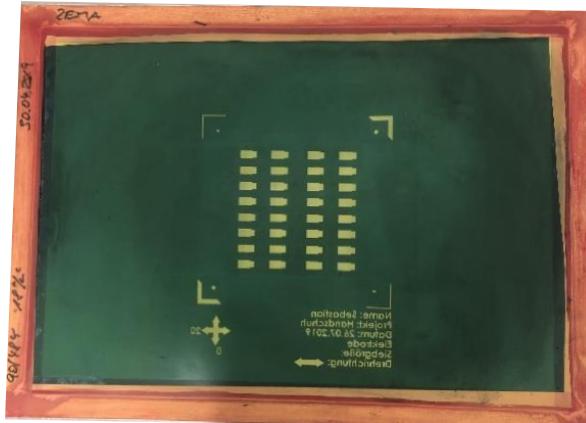
Prototype validation

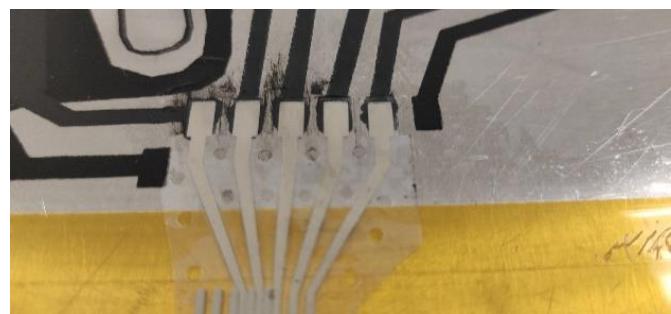
Summary and outlook



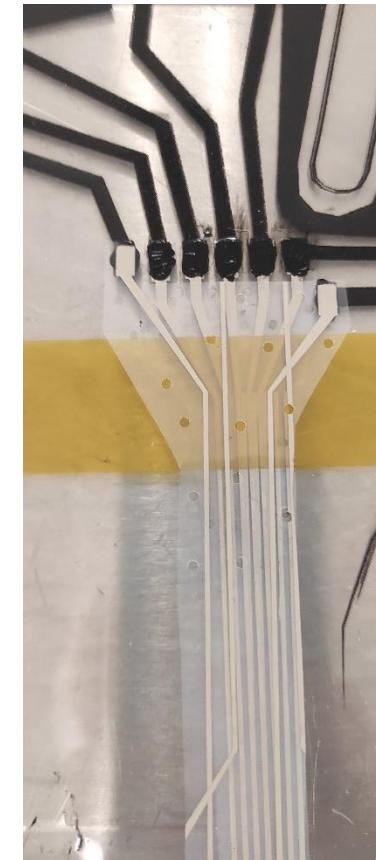


Printing the Electrodes

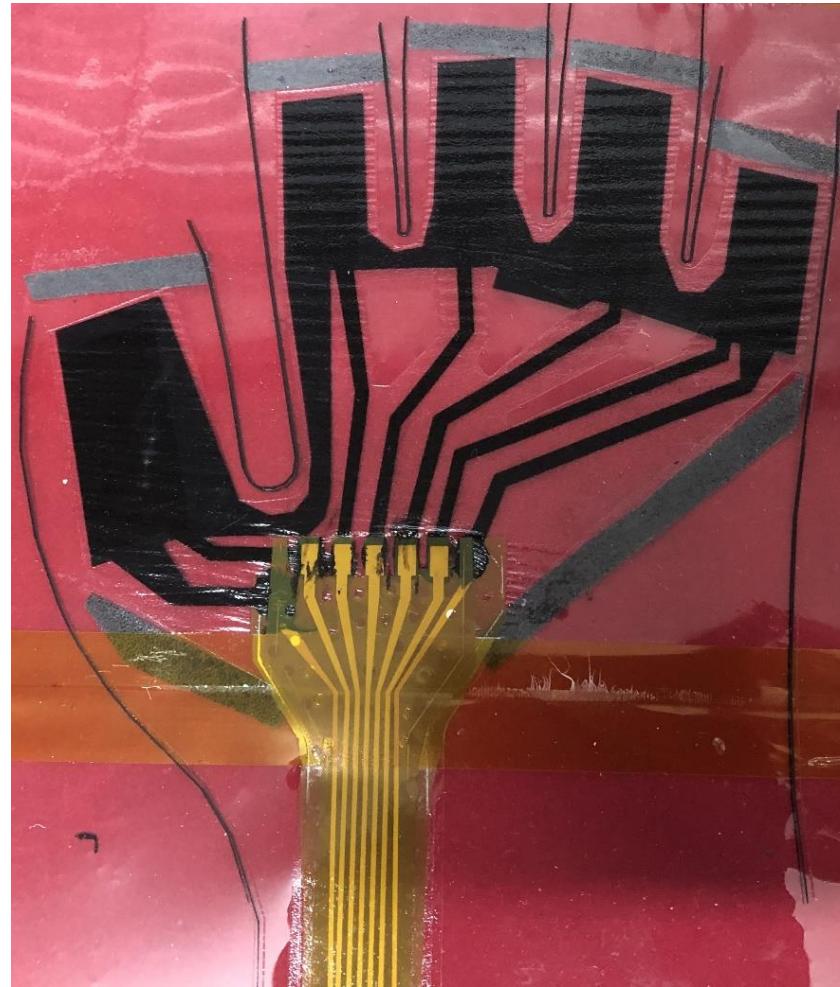




Silver printed conductor track glued onto the electrode



Screen-printed Protection layer
Textilstrips for sewing



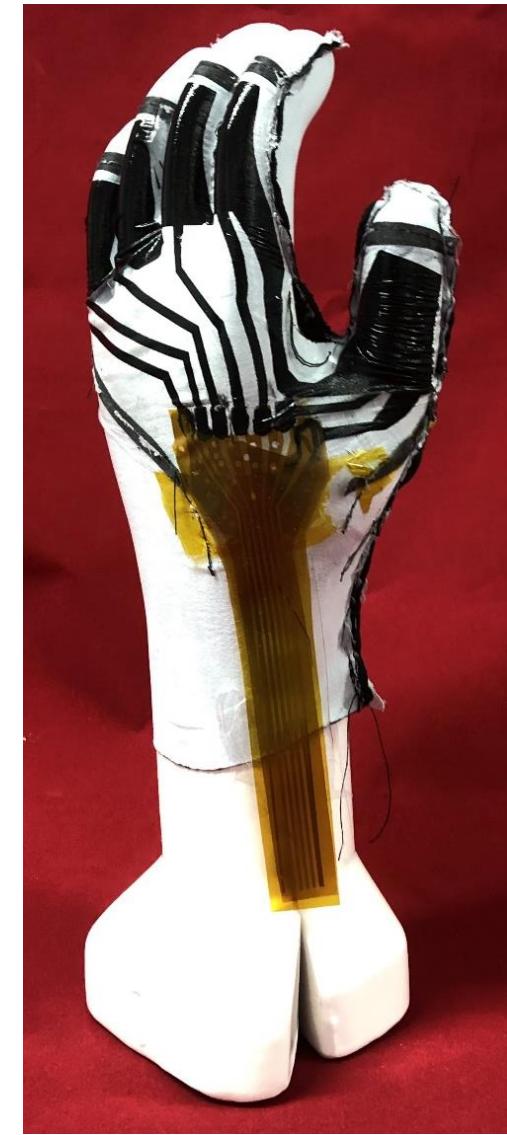
Ironing textile strips onto the silicone



Sewing textile strips onto the Glove textile



Cut out the glove pattern







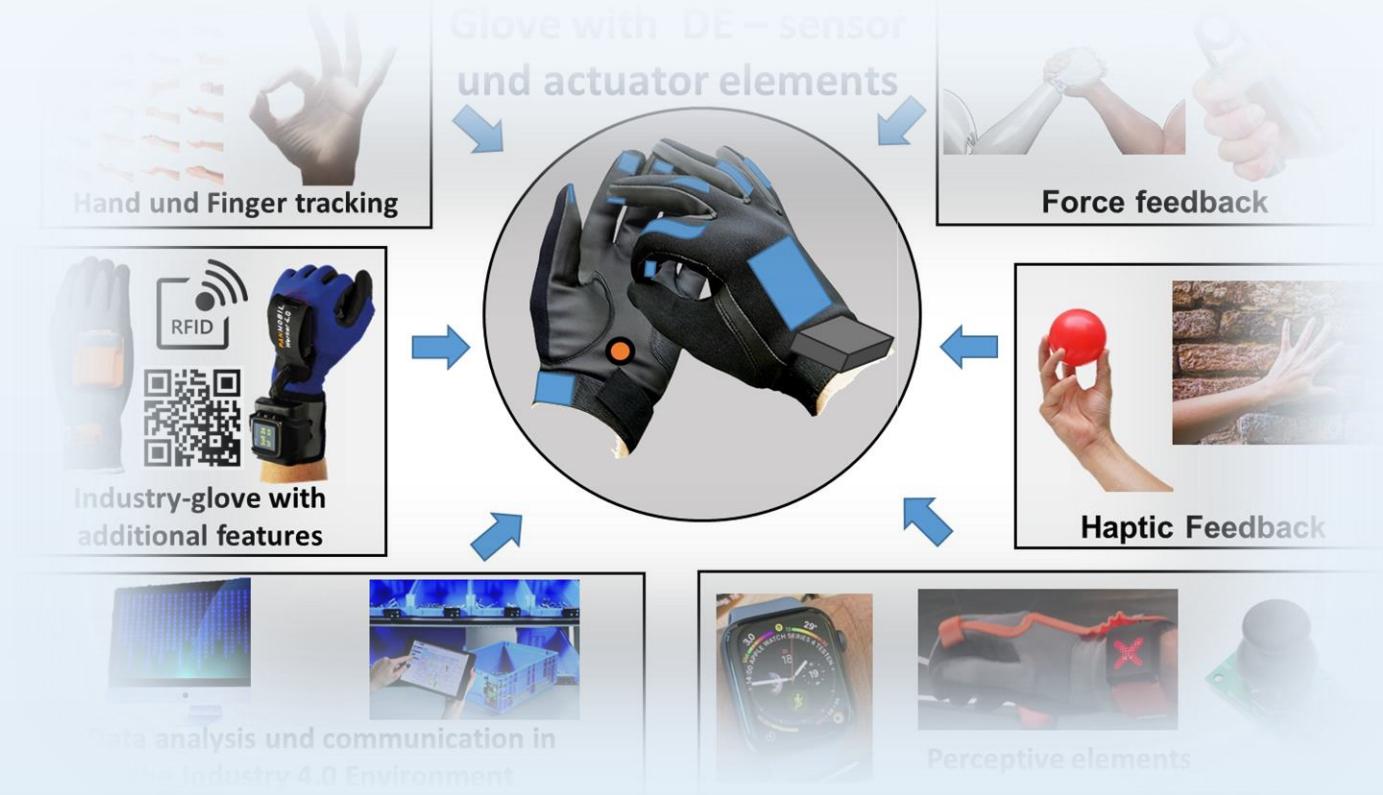
Structure of the assistance tool

- sensor
- actuator
- electronic
- integration

Prototype assembly

Prototype validation

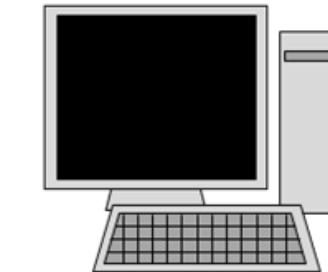
Summary and outlook



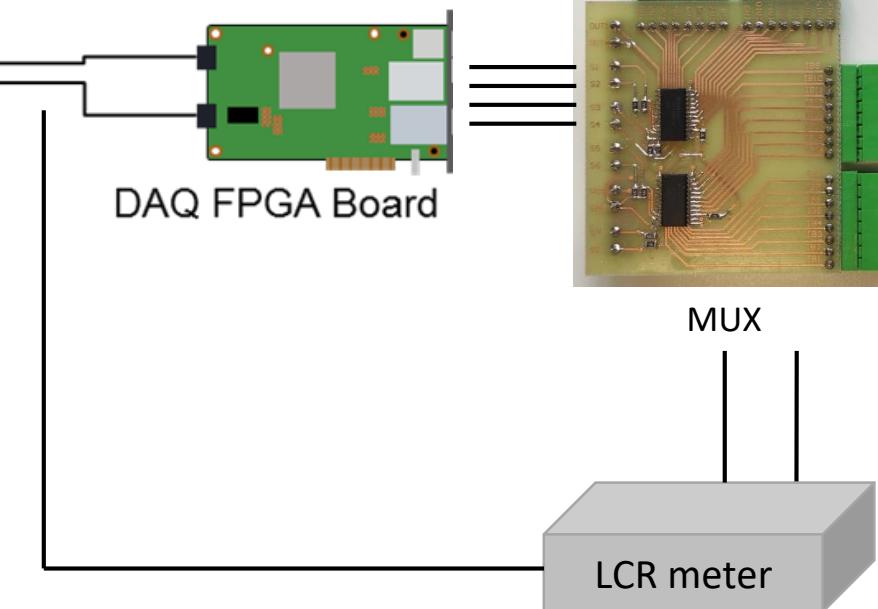
Prototype testing – measurement rig



Computer with
LabVIEW

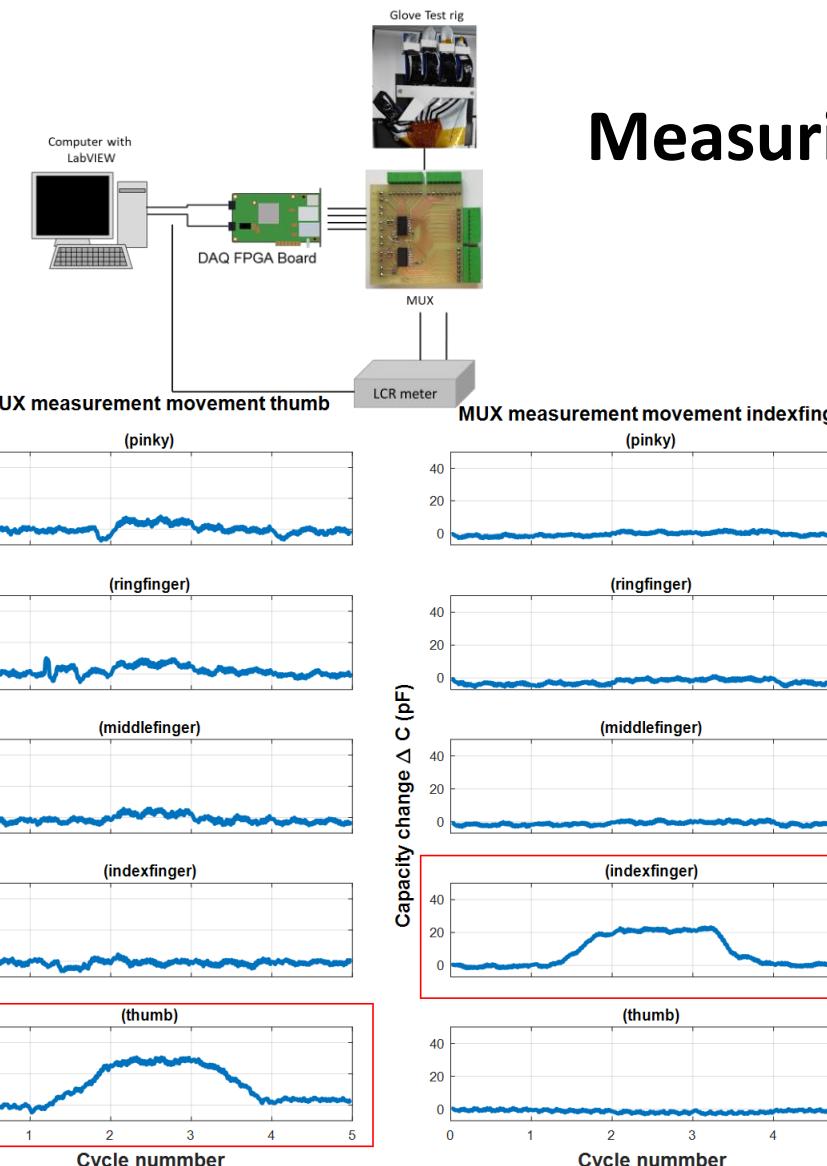


DAQ FPGA Board

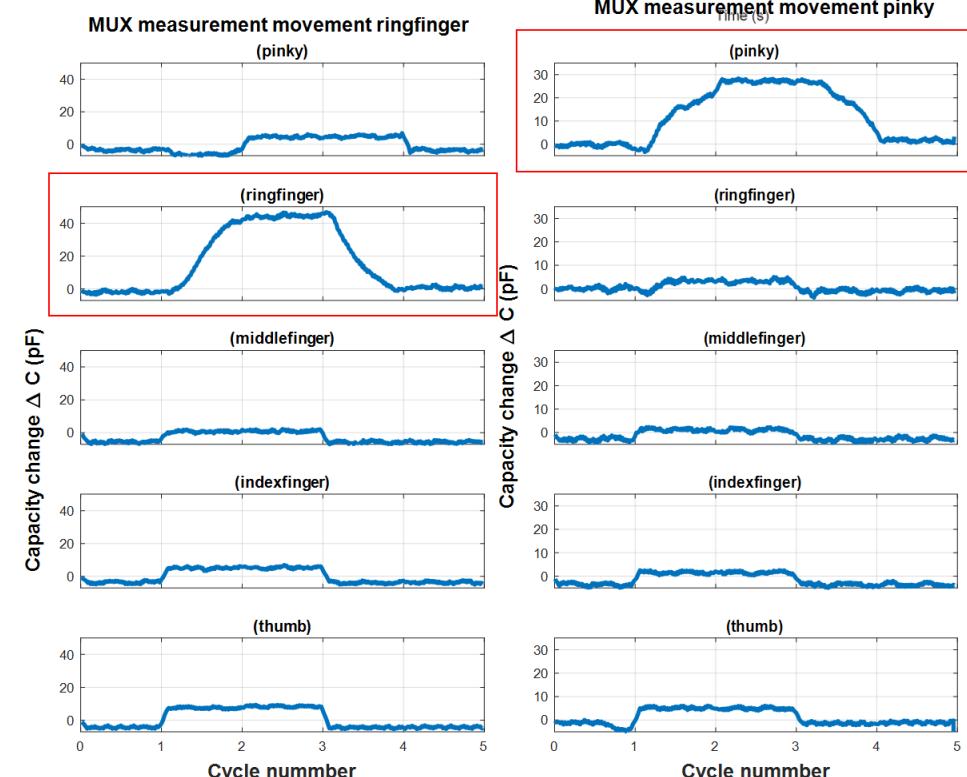
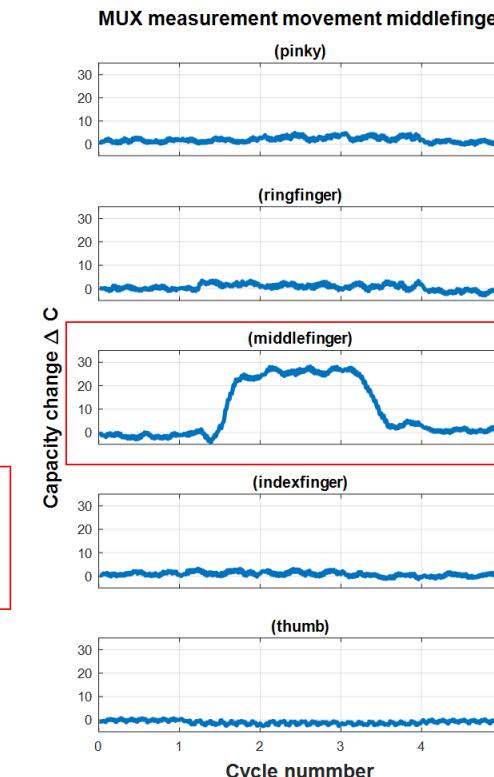


Glove Test rig





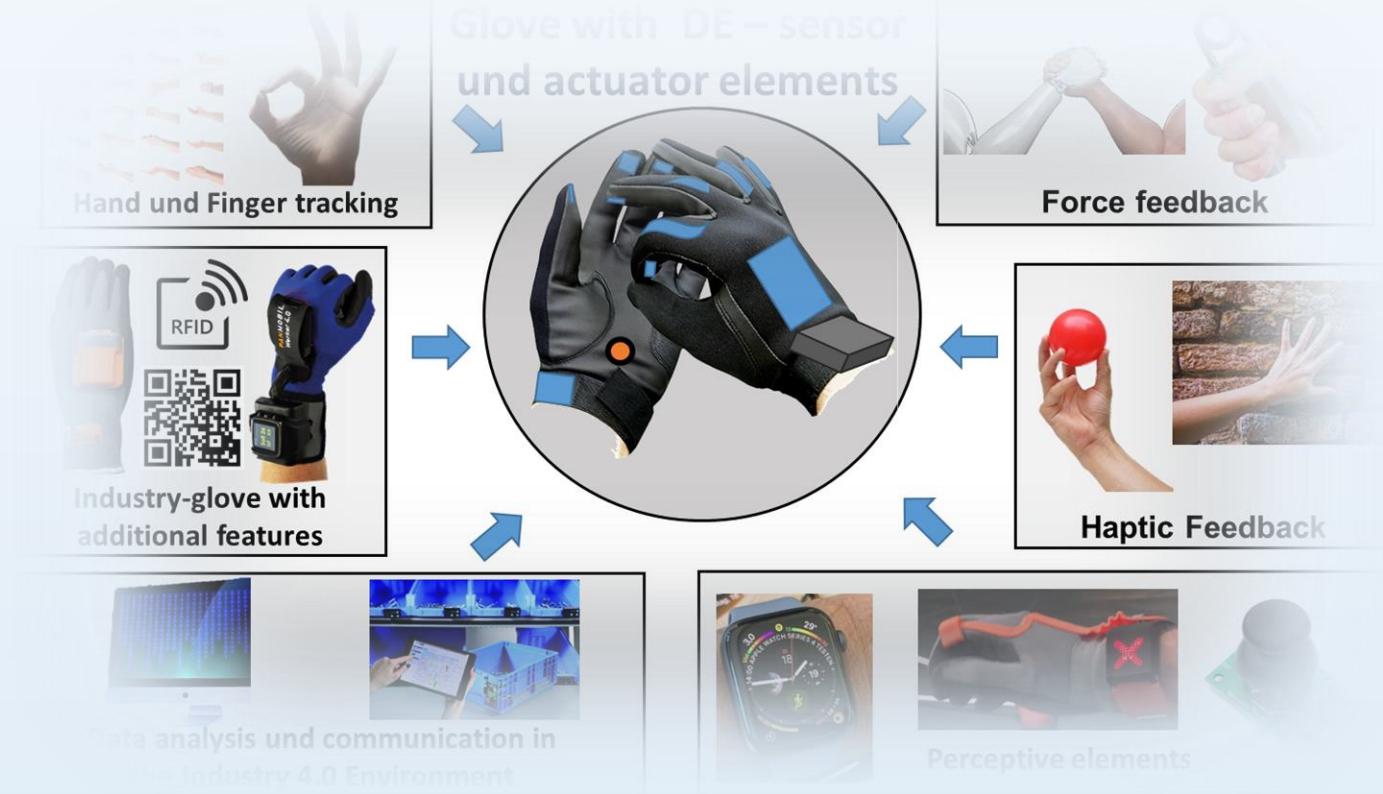
Measuring of different fingers bending





Structure of the assistance tool

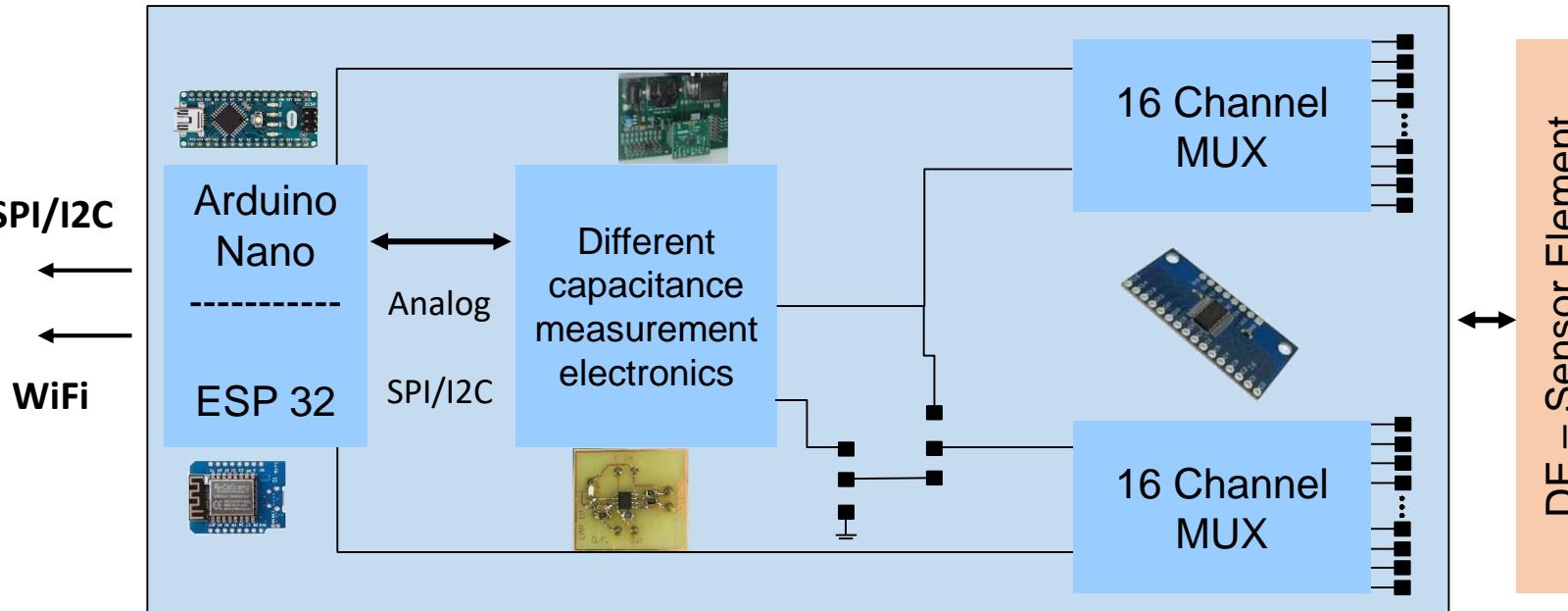
- sensor
- actuator
- electronic
- integration



Prototype assembly

Prototype validation

Summary and outlook



Circuit board

- 16 DE sensing differentially
- 32 DE sensing to Ground
- Flexible usage of different Microcontroller and Capacitance sensing IC's
- Potential usage of self developed NE555 circuit with additional IC for capacitance measurement

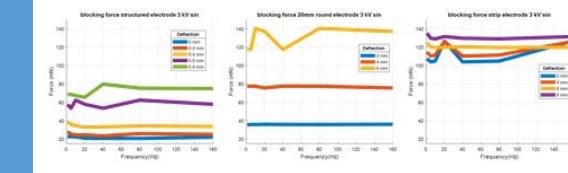
Combination:

Glove with sensor and actuator elements

High voltage and capacitance measurement electronic



- Prototype assembly (5 sensor element)
- Measurements with multiplexed sensor glove
- Haptic feedback
 - compared working principles
- Strip DE Design

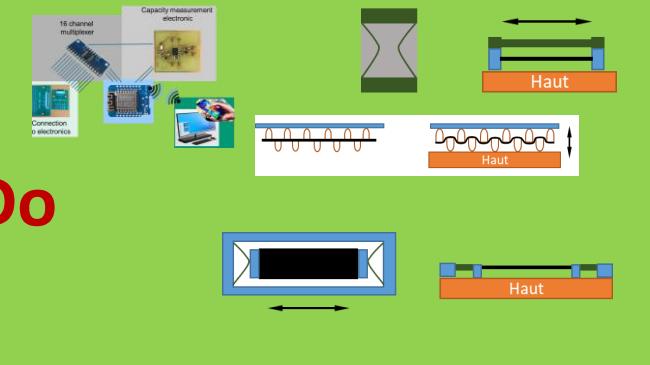


Summary



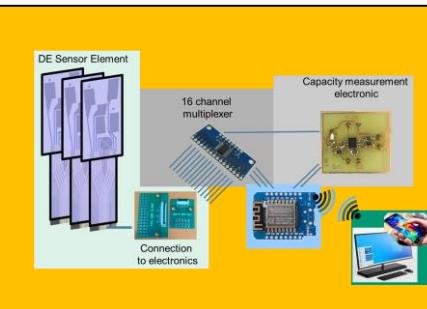
- Haptic feedback
 - Prototype manufacturing
- Haptic Feedback Prototype assembly (more Layer)
- Electronic development
 - Sensor circuit board
 - High voltage electronic

To Do



- Actuator development (additional elements)
- Multi sensor measurement
- Communication development
- Combination sensory and actuator electronic
- Miniaturized electronic board

Outlook





Thank you for your attention!



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Ze*/*MA

PROMOTIONS-
KOLLEG



DIGITALISIERUNG
DER PRODUKTION